

Engineered Cleaning Fluid and Mechanical Impingement Optimization Innovations

IPC Midwest Conference

Mike Bixenman, Kyzen Corporation

9-26-07



Electronic Interconnections Technology Trends

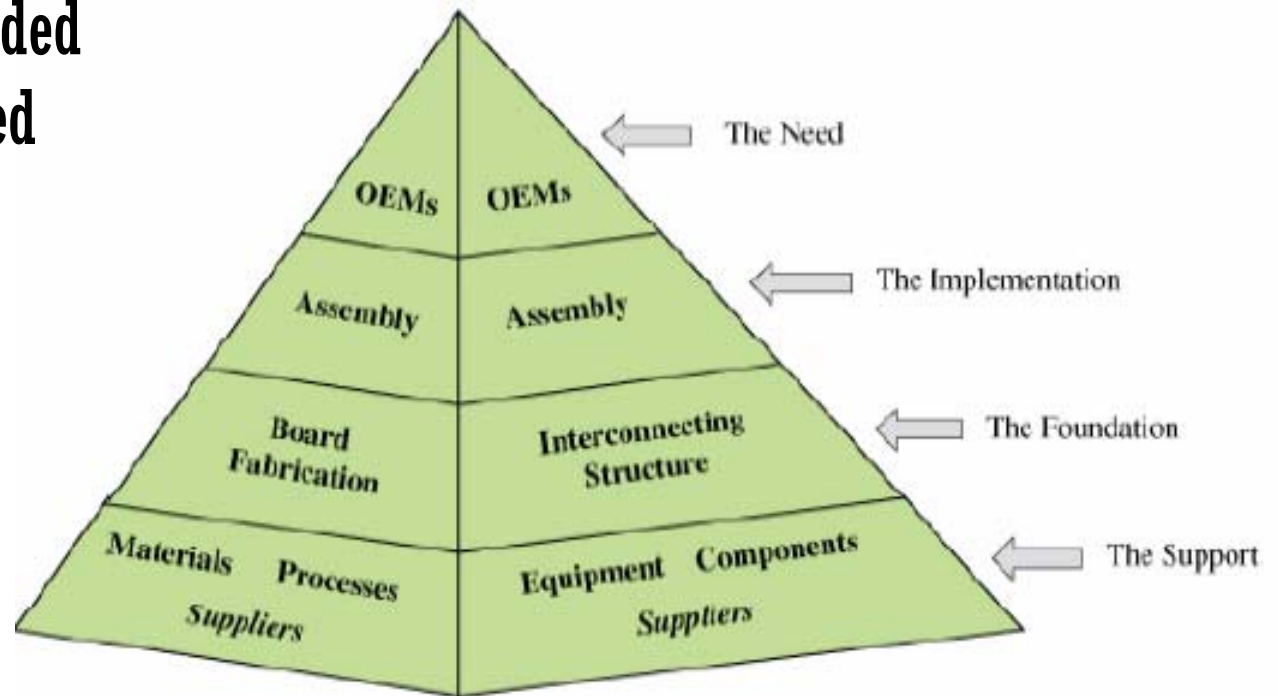
Situational Analysis

- Electronic interconnection industry experiencing rapid innovation to meet the
 - demand for greater functionality and performance
 - challenge of miniaturization and advanced designs
 - Never ending pressure for reduced cost
- Drivers for interconnection technology
 - Enhanced “System on a Chip” packaging
 - Higher Density
 - Better Reliability



Needs Assessment

- Do products or processes need improvement to maintain market share?
- Do technologies exist to meet the needs of each level of the pyramid?
- What advancements or investments are needed to accomplish defined roadmap goals?



IPC International Technology Roadmap, 2007

What is driving cleaning technology development?

Harsh Environments

- Automotive under the hood
- Military
- Avionics Electronics

Cleaning is a reliability driver



IPC International Technology Roadmap, 2007

Mid Range Performance Electronics

- High end personal computers
- High end games
- Networking telecommunications

*Advanced packaging
drives the need to clean*



High Performance Systems

- Mainframe
- Server
- Mass Storage
- RF
- Microwave

Bandwidth and signal impedance drive the need to clean.



IPC International Technology Roadmap, 2007

Hand Helds

- Cellular phones
- Sub-notebooks
- PDAs
- Hand held game

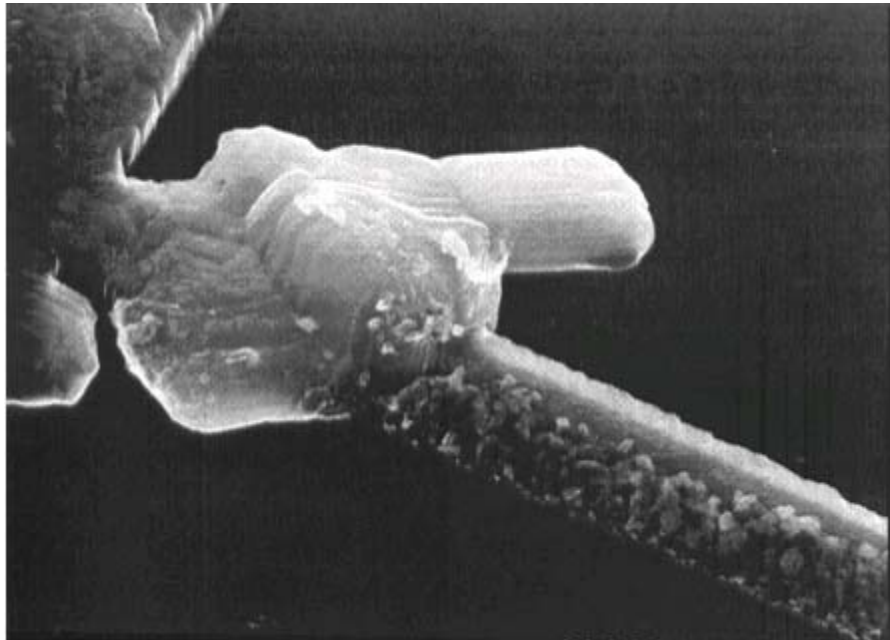
*System in package
driving the need to clean exacerbated
by Pb-free marketing programs.*



Failure Avoidance

This is why we are here today

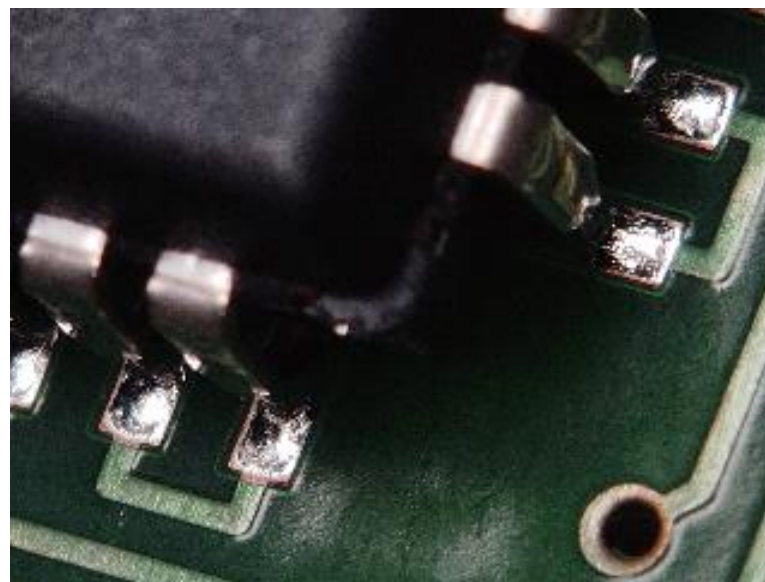
*Failures are bad
and cleaning can help
prevent failure at a systemic level*



Cleaning equates to Customer Value

- Cleaning is a key part of the solution for each of these challenges
- They all share the need for:
 - Increased miniaturization
 - Higher processing speeds
 - High frequency
 - Lower cost, better yields

*“A reliable assembly,
from a robust manufacturing environment”*

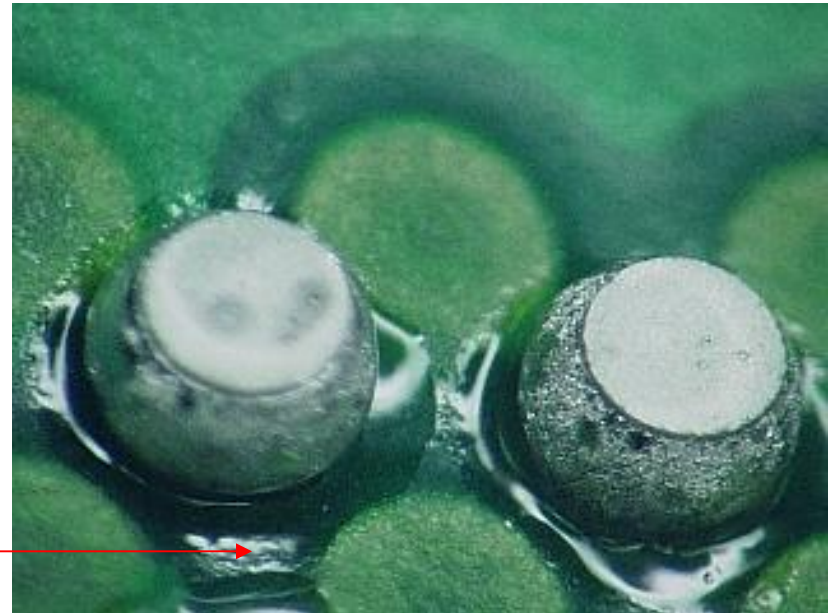


Electronic Interconnection Cleaning Technology

Cleaning Challenges have Evolved

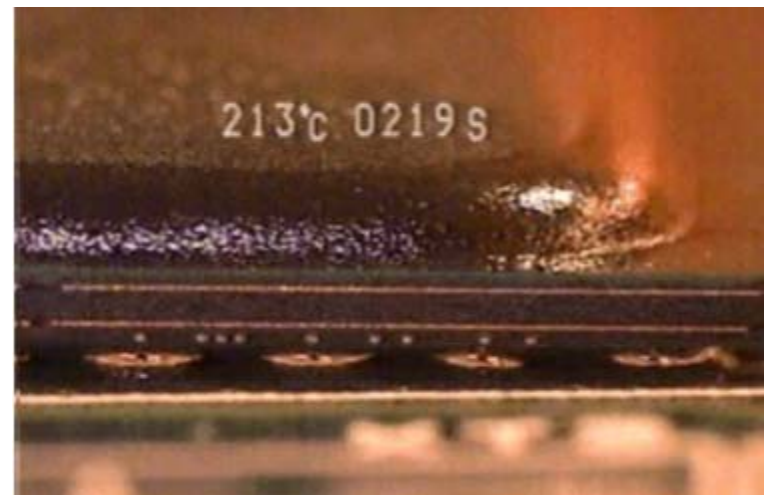
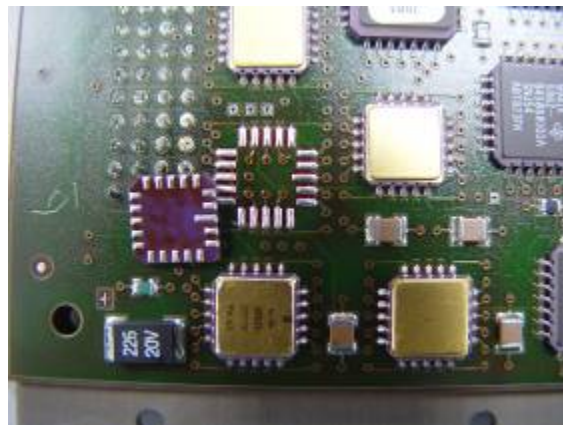
- Cleaning is increasingly more difficult due to:
 - Convergence of circuit board and advanced packaging technologies
 - Highly dense assemblies
 - Low standoffs
 - Pb-free flux is harder to clean

Flux Residue



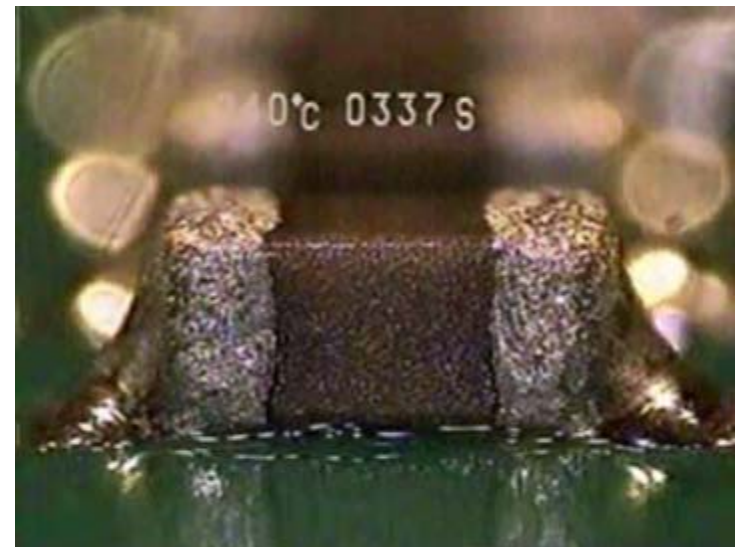
Difficult Cleaning Challenges

- Leadless chip carriers
- Flush mounted chip caps
- Area array components
- Capillary action and surface tension fill the underside of the components flux residue



Problem Definition

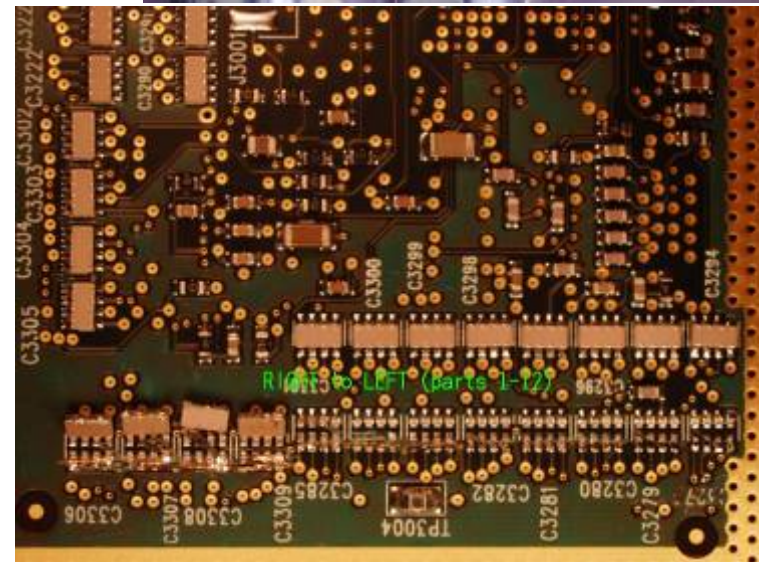
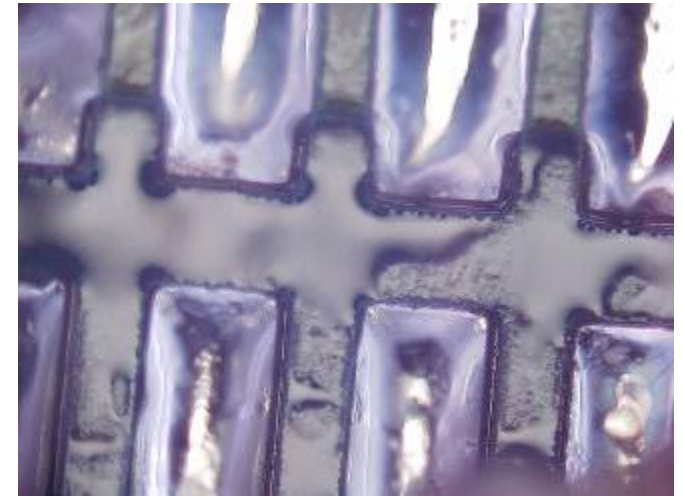
- Average spacing under one of these devices is approximately 2-4 mils
 - Chip caps can be as low as 1 mil
- To clean under these components
 - Static and dynamic cleaning rates must
 - Break the flux dam
 - Impinge the leading edge with pressure and flow
 - Cleaning fluid that rapidly dissolves the residue
- Drivers for removing all flux residues
 - Cleaning fluid
 - Wash time
 - Wash temperature
 - Pressure, flow, and directional forces



Approach to Solving Unmet Cleaning Needs

Optimizing the Cleaning Process

- Requires an understanding of ...
 - Upstream considerations
 - Static driving forces
 - Mechanical driving forces
- As the component gap reduces
 - *Cleaning becomes more difficult*



Process Optimization

IDEAL FUNCTION DIAGRAM WASH PROCESS

NOISE

1. Variety of flux chemistries washed at the same time.
2. Amount of flux on the board.
3. Flux oxidation on from excessive reflow/wave heat.
4. Flux allowed to cool/dry on the board. Excess time before cleaning
5. Density/complexity of CCA.
6. Other and unknown soils on the board.

Soldered CCA

CONTROLS

1. Reflow/Wave profile
2. Type of flux/paste
3. Time between soldering and washing
4. Side A or Side B up in the wash.
5. Board processes in a basket or not

NOISE

1. Drag out into rinse module
2. Incoming water condition
3. Refractive Index MSA
4. Age of the wash bath
5. Volume of work processed at a given time.
6. Mixed flux chemistries from different boards styles.
7. Evaporative loss of wash solution.

Wash

CONTROLLING PARAMETERS

1. Conveyor Speed (Dwell time)
2. Cleaner concentration
3. Wash temperature
4. Rinse temperature
5. Nozzle Types (Flow vs. Pressure)
6. Nozzle direction, top/bottom
7. Manifold/spray pressure, top/bottom

DESIRED CHARACTERISTICS

1. All flux residues removed.
2. No contaminants (white residue, oil)
3. Marking intact.
4. No corrosion

Cleaned Assemblies

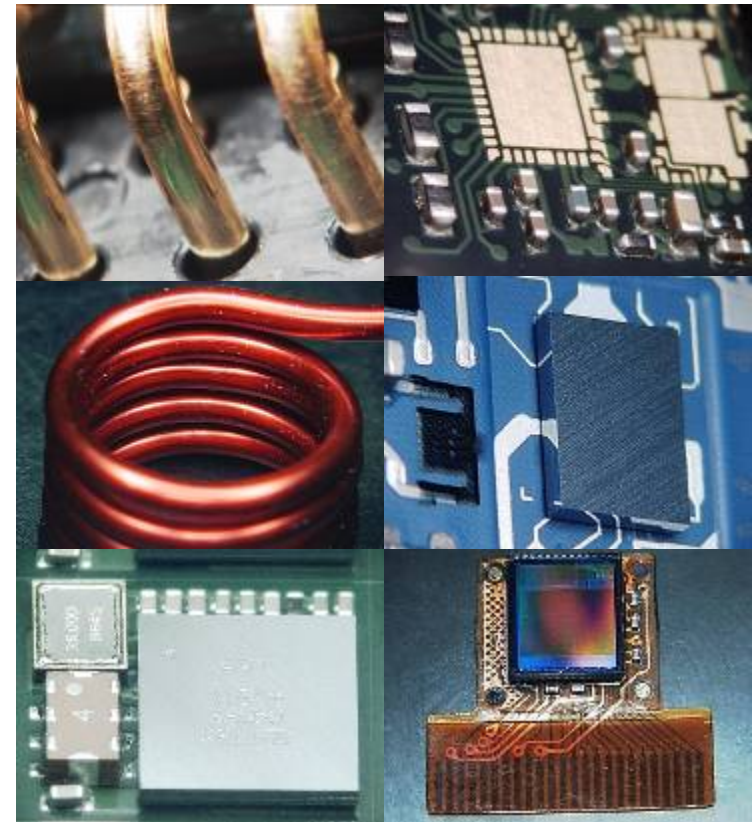
DEFECTS & FLAWS

1. White residue
2. Contaminants (oil/grease)
3. Cleaning agent left on board
4. Corrosion
5. Marking removed or washed out.

(Bixenman, Gervascio, Lasky, 2007)

Upstream Considerations

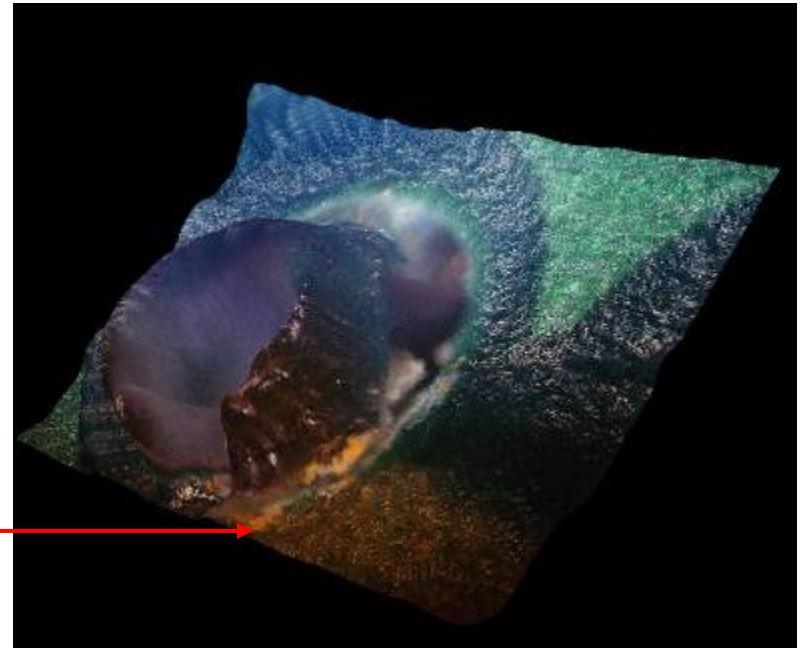
- Cleaning fluid must be designed
 - Around equipment types
 - For the soil
 - For the application
- Electronic cleaning needs
 - Rapid removal of soil
 - Low surface tension/wetting
 - Repeatability
 - Controllable
- Cleaning equipment
 - Building blocks must be matched to the specific cleaning requirement



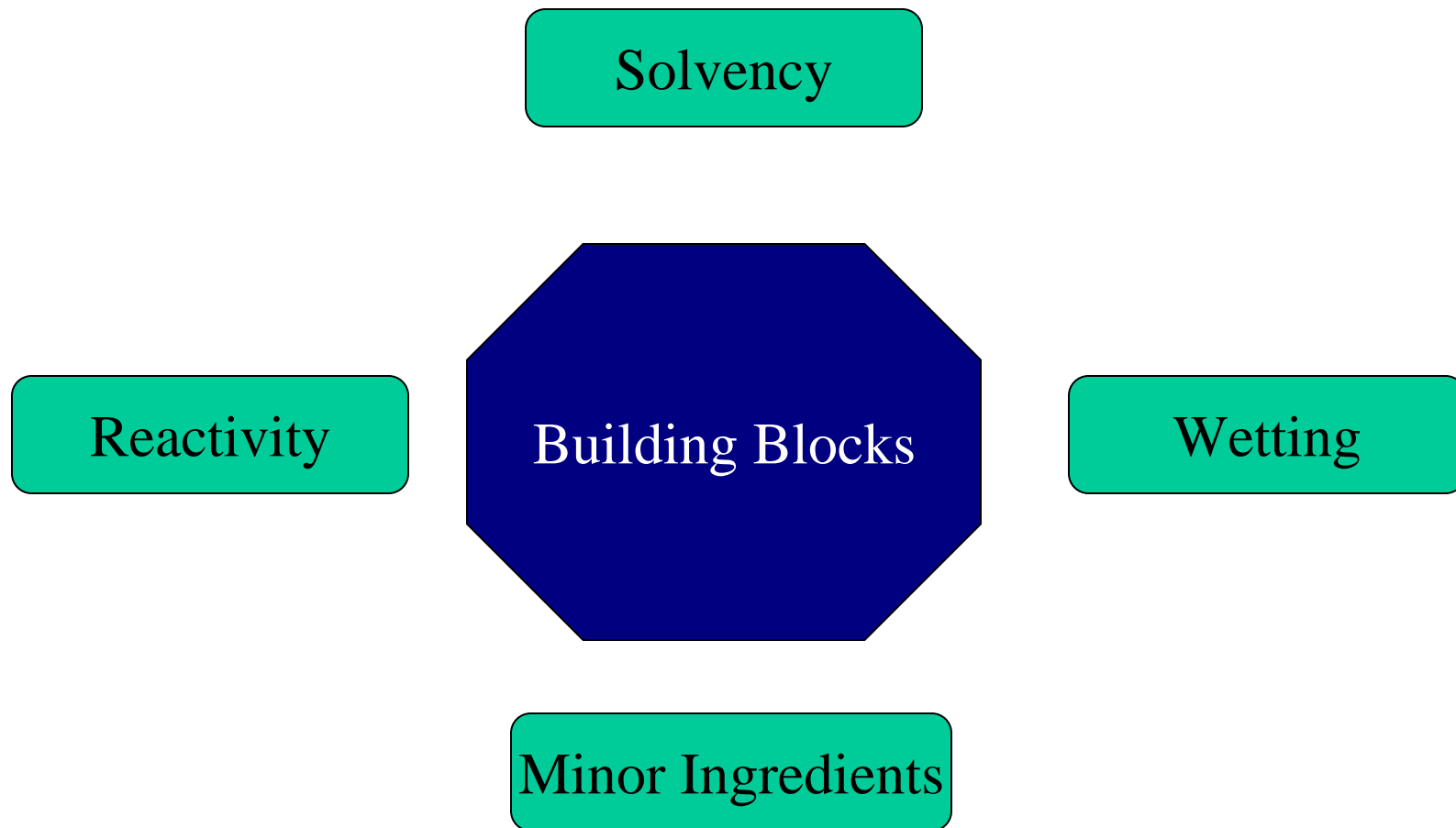
Influential Variables

- Many variables influence the process cleaning rate
 - Substrate
 - Contaminant
 - Wash Temperature
 - Wash time
 - Cleaning fluid
 - Mechanical impingement
 - Surface tension (capillary action)

White Residue



Cleaning Technology Basics

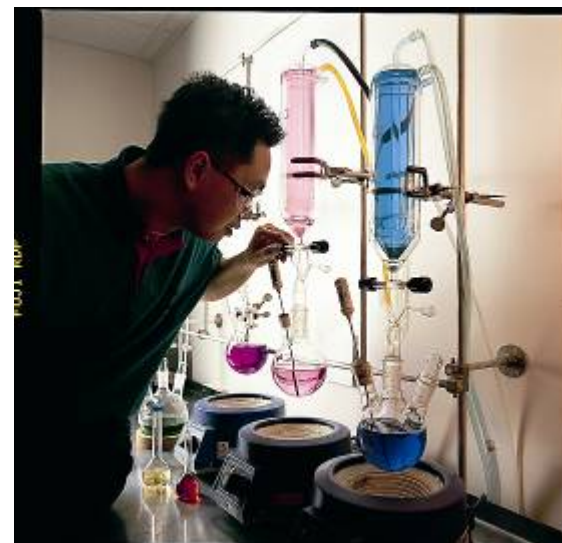


Cleaning Fluid Building Blocks

- Engineered aqueous materials that consist of:
 - solvating materials
 - dissolve resins, rosin and polymeric structures
 - wetting materials
 - reduce wash chemistry surface energy and droplet size
 - activators
 - rapidly softens resins, which allows dissolution in the wash media
 - minor ingredients
 - inhibition to prevent oxidation
 - destabilizing foam

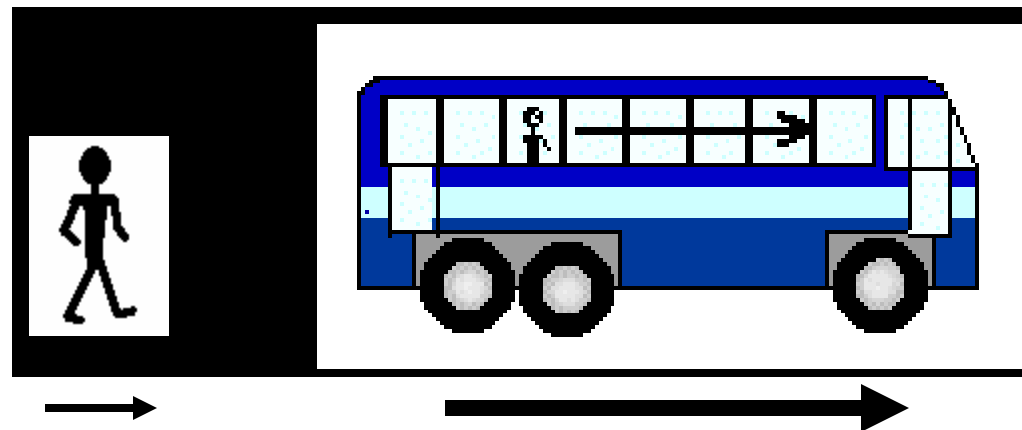
Cleaning Fluid Goals

- Built on the principle of lean technology
- Product improvements are built from
 - Improved solvency to remove flux soils
 - Operate at lower concentrations ~ 5-15% range
 - Operate at lower wash temperatures ~ 110 -150°F
 - Operational consistency
 - Long bath life
 - No foam
 - Controllable
 - Environmental improvements
 - Compatibility improvements



Rate Theory

“The over-all process cleaning rate is sum of the static rate plus the dynamic rate”



$$50 \text{ MPH} + 50 \text{ MPH} = 100 \text{ MPH}$$

Static Rate + Dynamic Rate = Total Rate

Static Rate = Rate at which process will proceed on its own

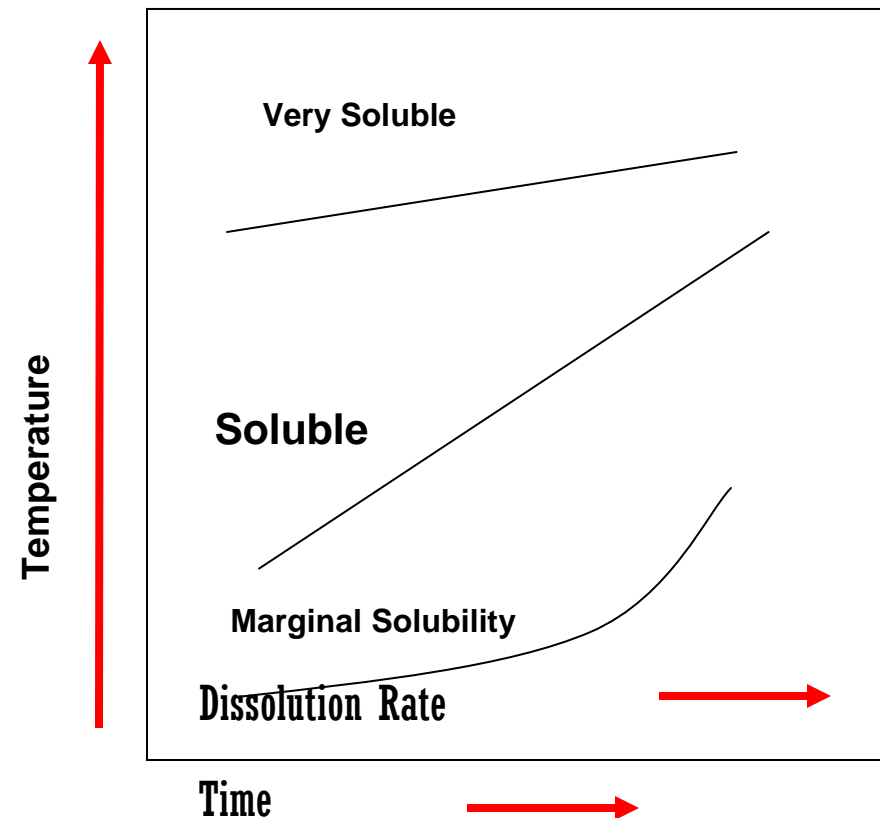
Dynamic Rate = Rate increase attributable to machine

Stach, Bixenman (2005)

Cleaning Rate Theory Details

- Chemical Driving Forces
 - Dissolution rate
 - Temperature
 - Time
 - Cleaning fluid concentration
 - Surface Tension
 - Wetting
- Mechanical Driving Forces
 - Flow
 - Impingement
 - Direction
 - Fluid Pattern

Fluid Dynamics

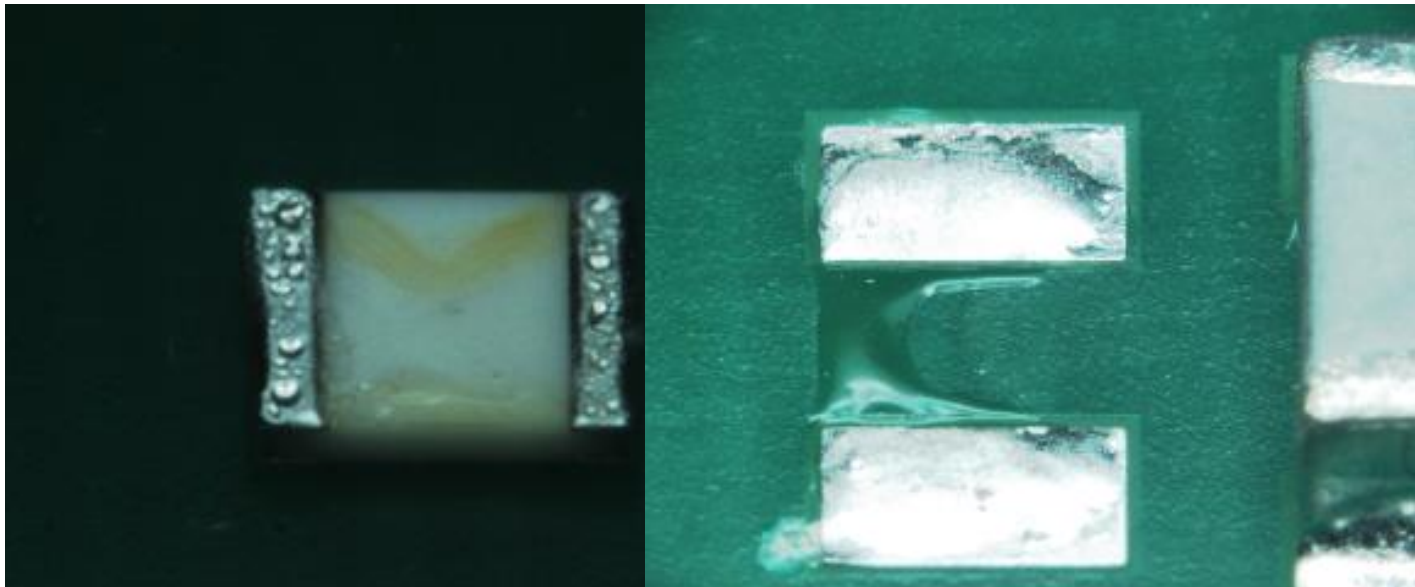


Process Implications of the Cleaning Rate Theory

- **Concentration** of the cleaning fluid
 - Higher concentration tends to improve cleaning performance
- **Temperature**
 - Solder flux tends to remove better at 130-160°F range
- **Time**
 - Longer time improve cleaning ~ especially under low standoffs
- **Impingement**
 - Combination of soak, flow and high pressure improve cleaning

Low Stand Offs: Complicate the Theory

- Rate theory fails to apply in all cases, specifically where penetration is required to reach the soil.
- The cleaning fluid must get to the soil before the cleaning fluid will dissolve or react

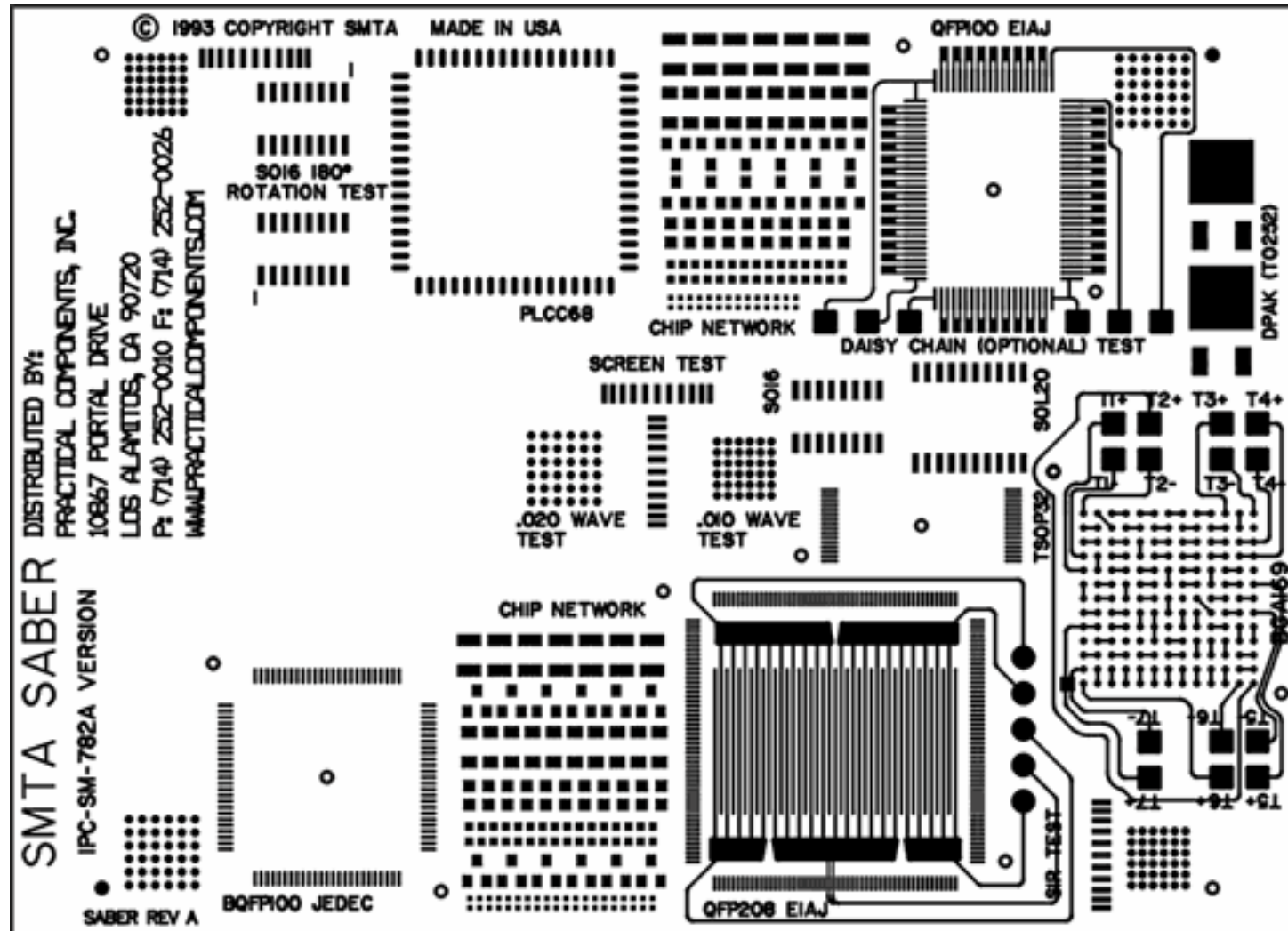


Methodology

- **Static cleaning rate**
 - **SMTA Saber Board**
 - Residue removal around fine pitch components
 - Factorial Design
 - Batch dishwasher style cleaning machine with low impinging forces
- **Dynamic cleaning rate**
 - Selection of cleaning fluid that provides highest static cleaning rate
 - Evaluate the design and layout of nozzles
 - Nozzle types for penetrating under low standoff components
 - Time under manifold to clean under low standoff components
 - Optimization of nozzles to facilitate cleaning under low standoff components

Static Cleaning Rate

Test Vehicle



Factors

Factor Description	Level 1	Level 2
Reflow Profile	Low Thermal Load	High Thermal Load
Number of Reflows	1	2
Cleaning Residence Time	8 min	16 min
Cleaning Chemistry	Chemistry 1 @ 13% & 125F based on pre-test findings	Chemistry 2 @ 20% & 150F based on pre-test findings

DOE

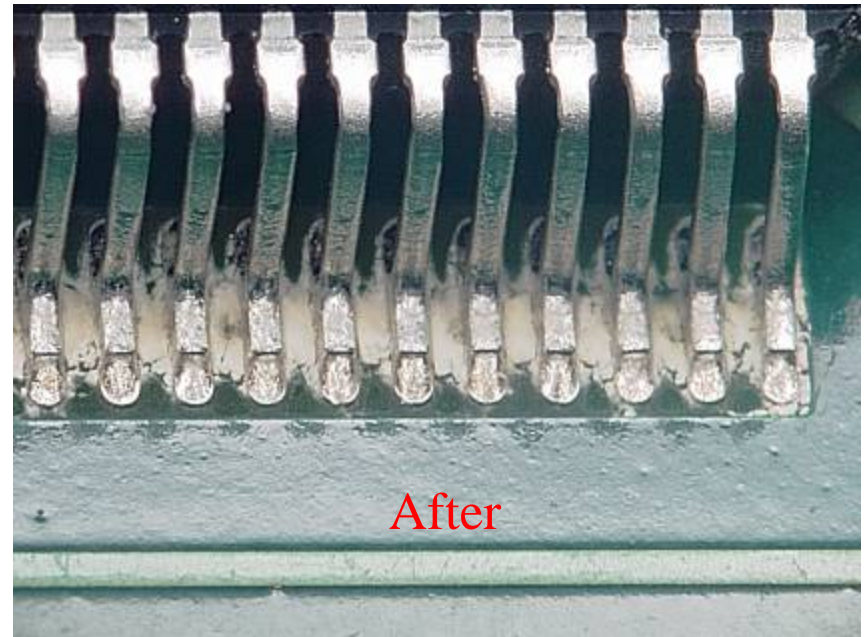
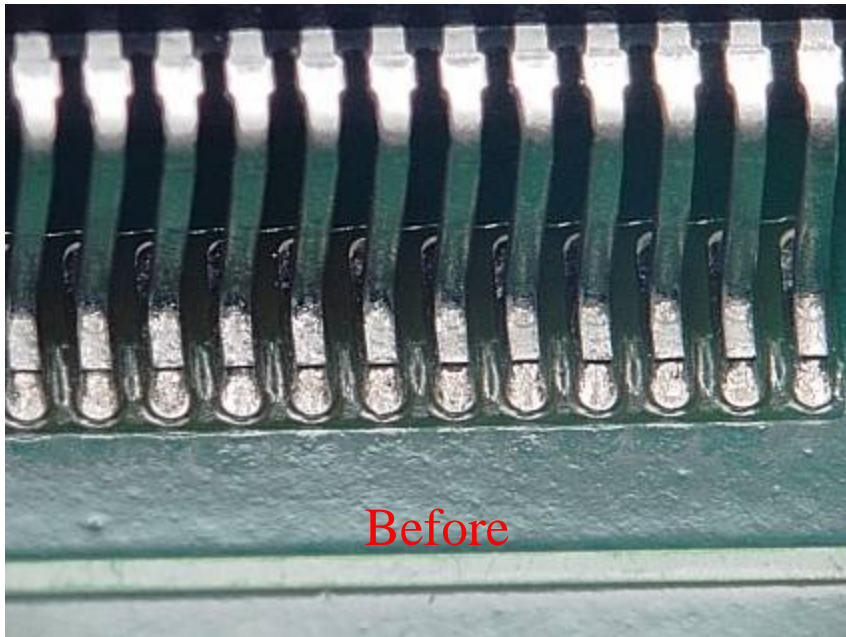
Run	Reflow Profile	No of Reflows	Cleaning Time	Wash Temp.	Conc.	Chemical
1	Low	1	8	125°F	13%	Chemistry 1
2	High	1	8	125°F	13%	Chemistry 1
3	Low	2	8	125°F	13%	Chemistry 1
4	High	2	8	125°F	13%	Chemistry 1
5	Low	1	16	125°F	13%	Chemistry 1
6	High	1	16	125°F	13%	Chemistry 1
7	Low	2	16	125°F	13%	Chemistry 1
8	High	2	16	125°F	13%	Chemistry 1
9	Low	1	8	150°F	20%	Chemistry 2
10	High	1	8	150°F	20%	Chemistry 2
11	Low	2	8	150°F	20%	Chemistry 2
12	High	2	8	150°F	20%	Chemistry 2
13	Low	1	16	150°F	20%	Chemistry 2
14	High	1	16	150°F	20%	Chemistry 2
15	Low	2	16	150°F	20%	Chemistry 2
16	High	2	16	150°F	20%	Chemistry 2

Responses

- The responses measured were visual examination of flux residues after reflow and cleaning processes. Printed circuit assembly was inspected around the QFP component. Two orientations were inspected and graded on a 1-10 scale.
- A “1” designated that no flux was removed. A “10” designated that 100% of flux residue was removed. Inspection was conducted under 10X magnification. One set of leads inspected was 90 degrees rotated from first set of leads.

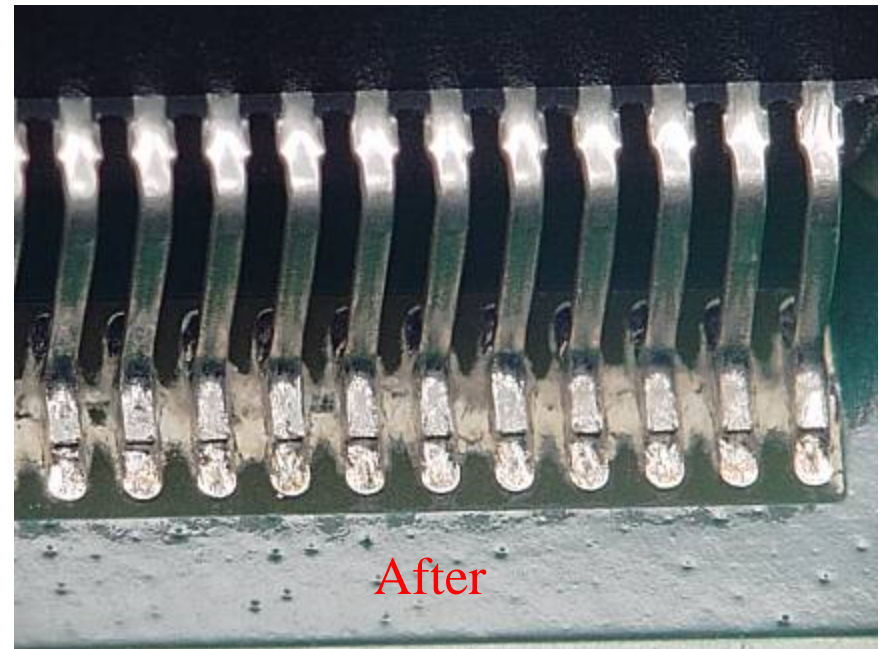
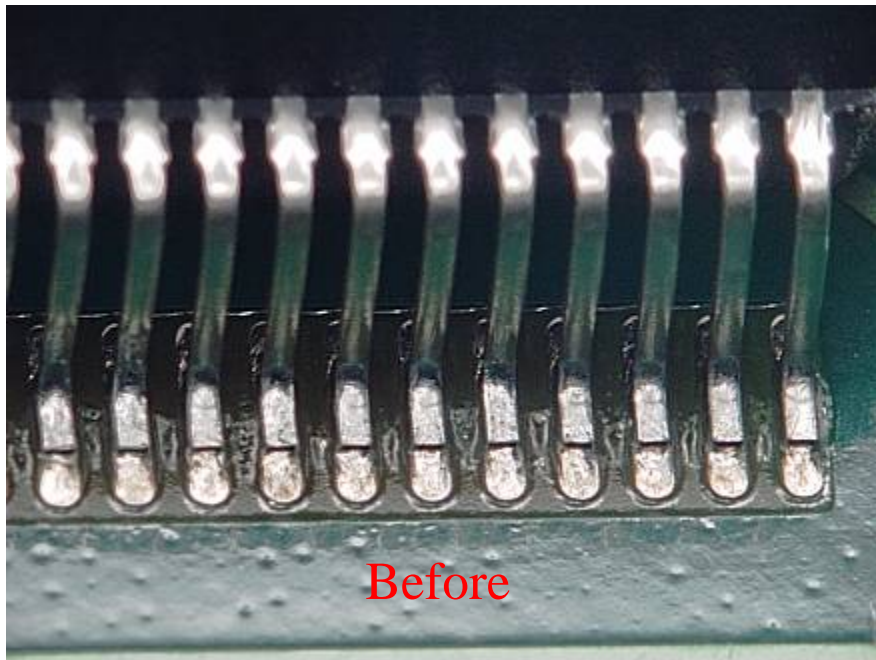
Chemistry 1

- Low Reflow Profile (Peak 230°C)
- One reflow exposure
- 8 minute wash time, 125°F, 13%



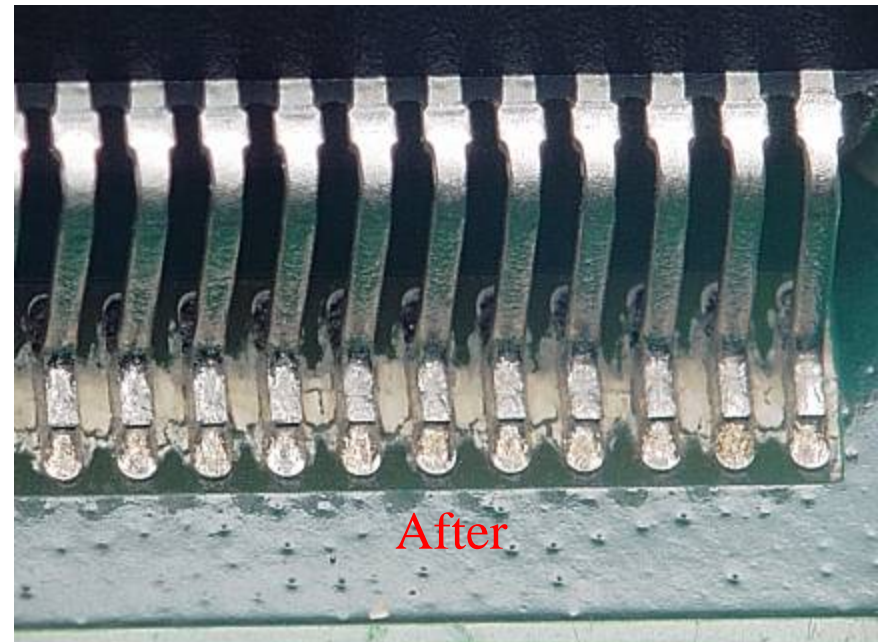
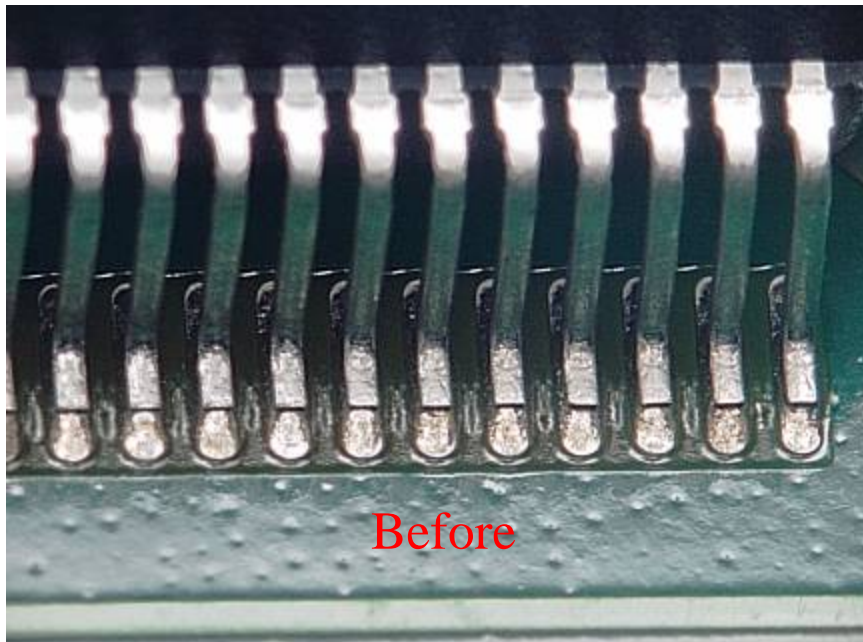
Chemistry 1

- High reflow profile (Peak 250°C)
- One reflow exposure
- 8 minute wash time, 125°F, 13%



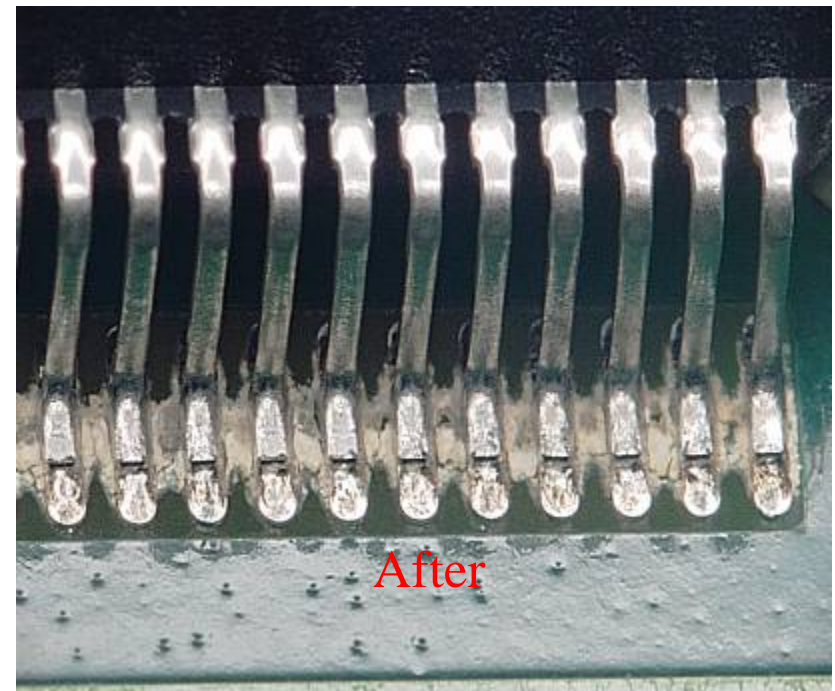
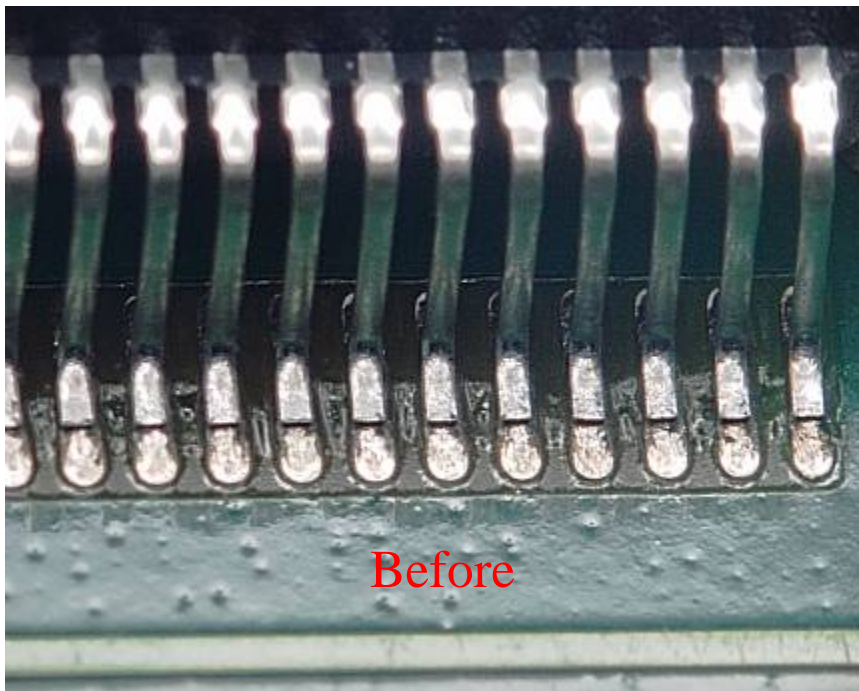
Chemistry 1

- Low Reflow Profile (Peak 230°C)
- Two reflows exposure
- 8 minute wash time, 125°F, 13%



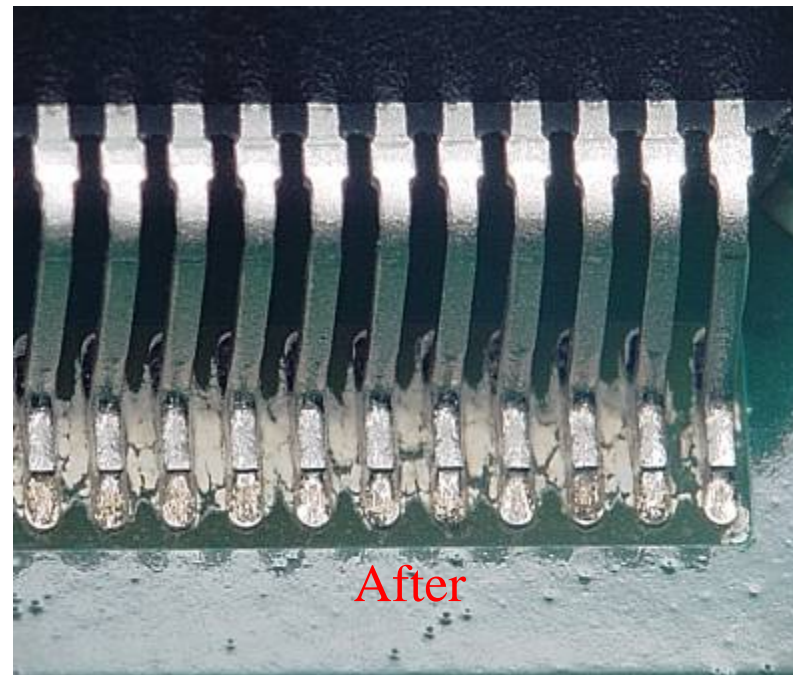
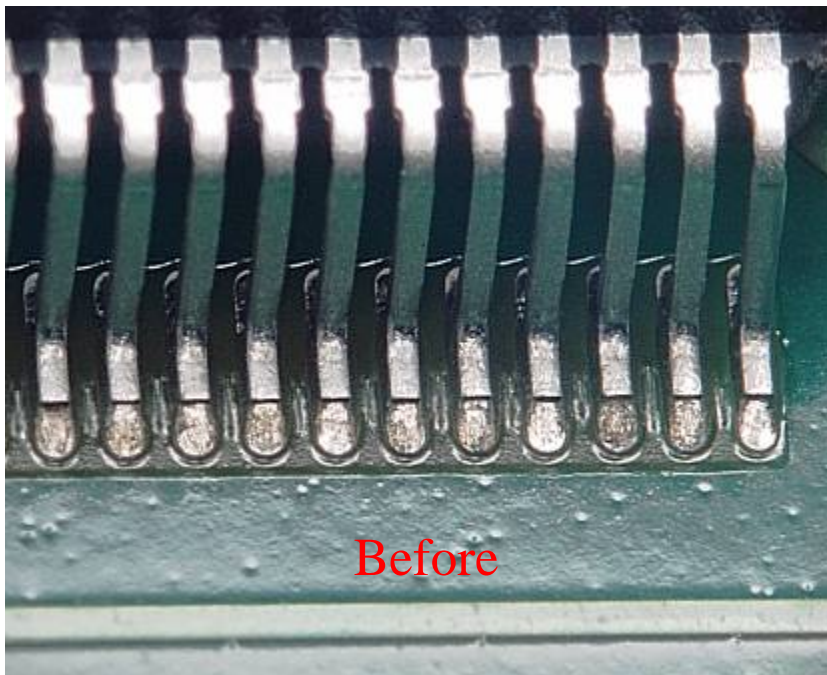
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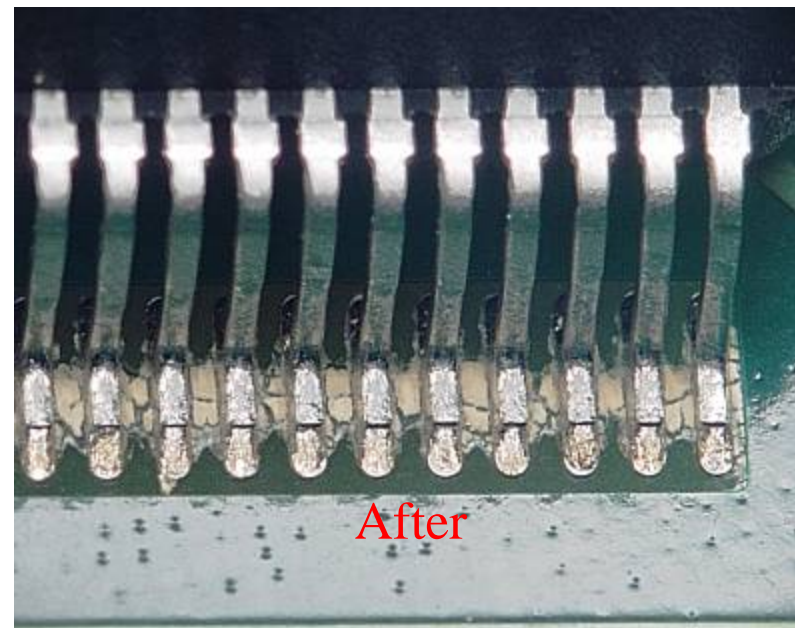
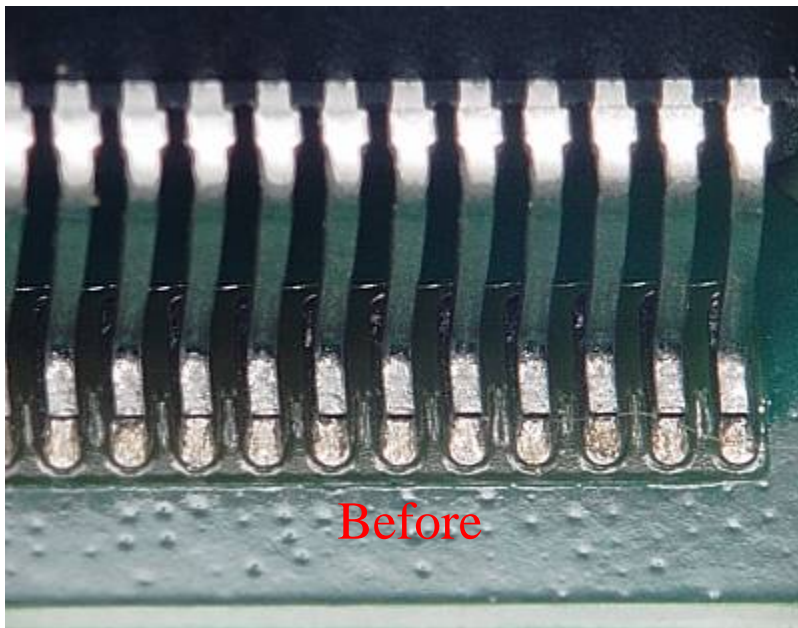
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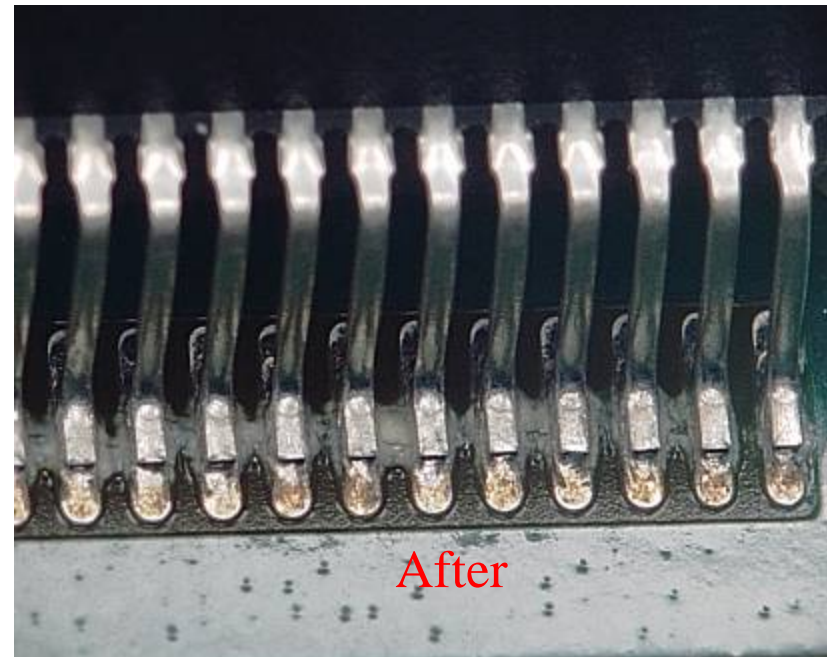
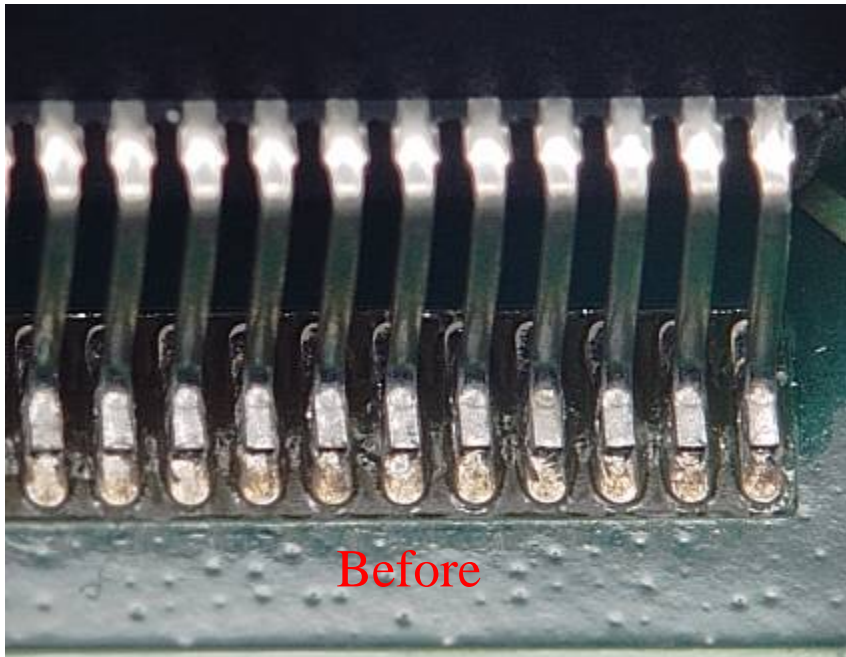
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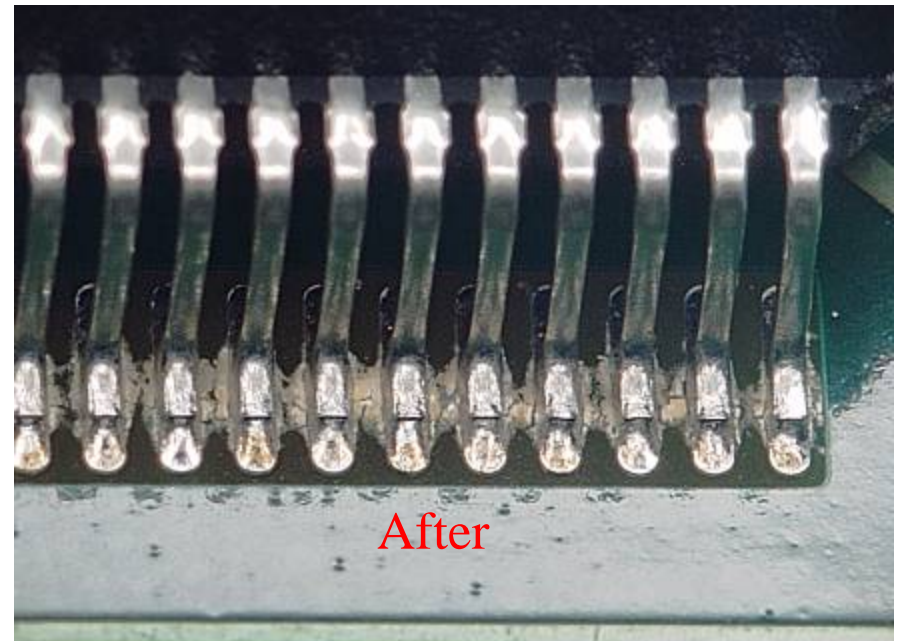
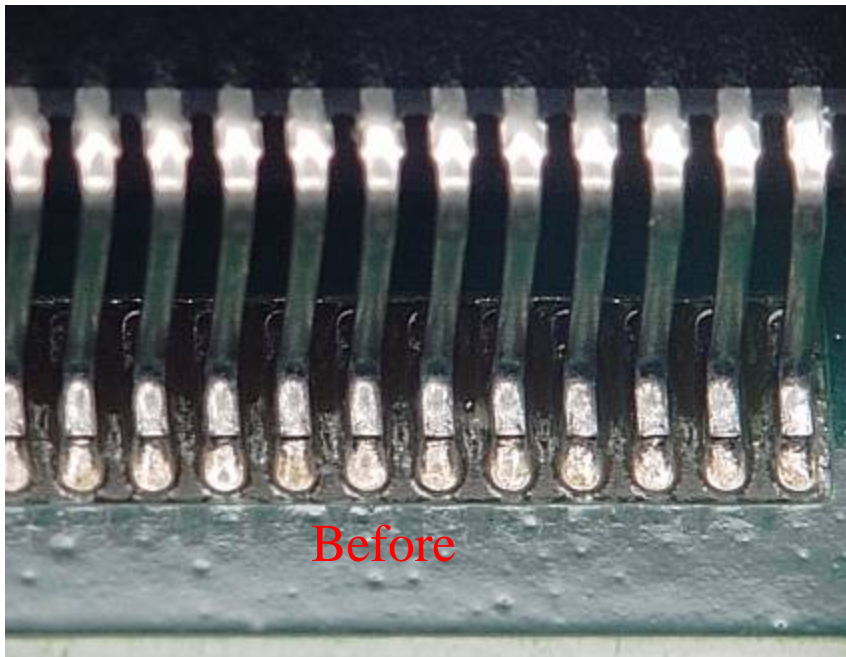
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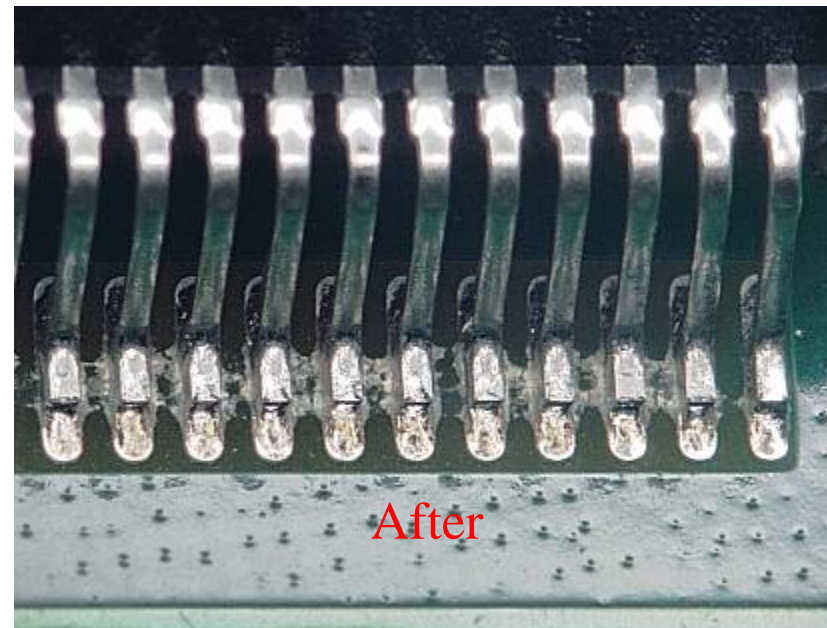
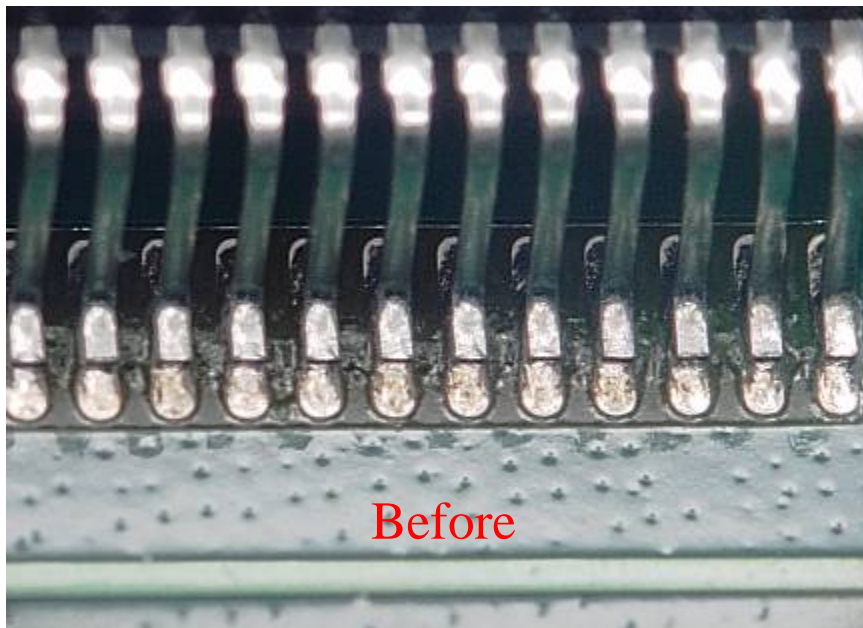
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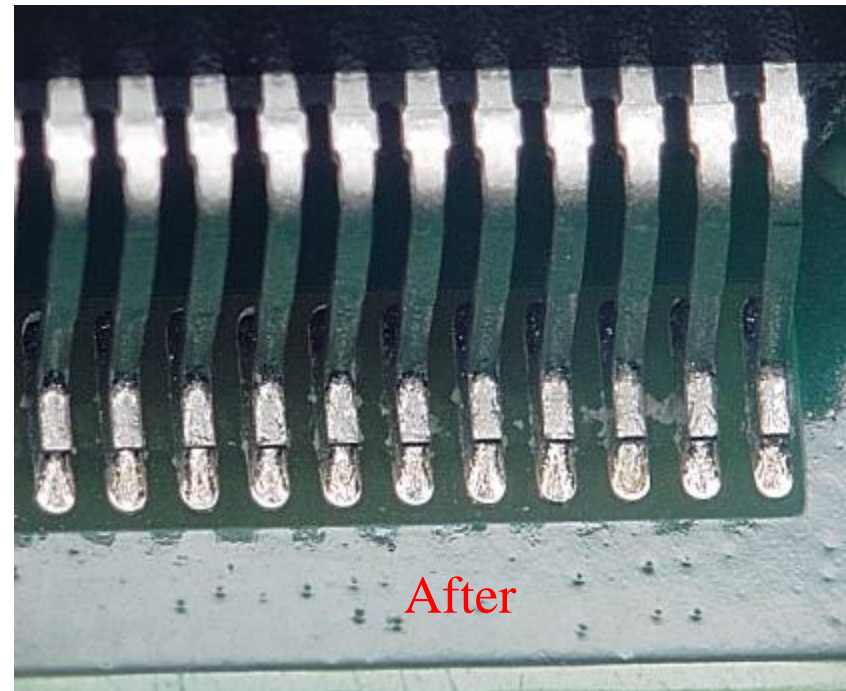
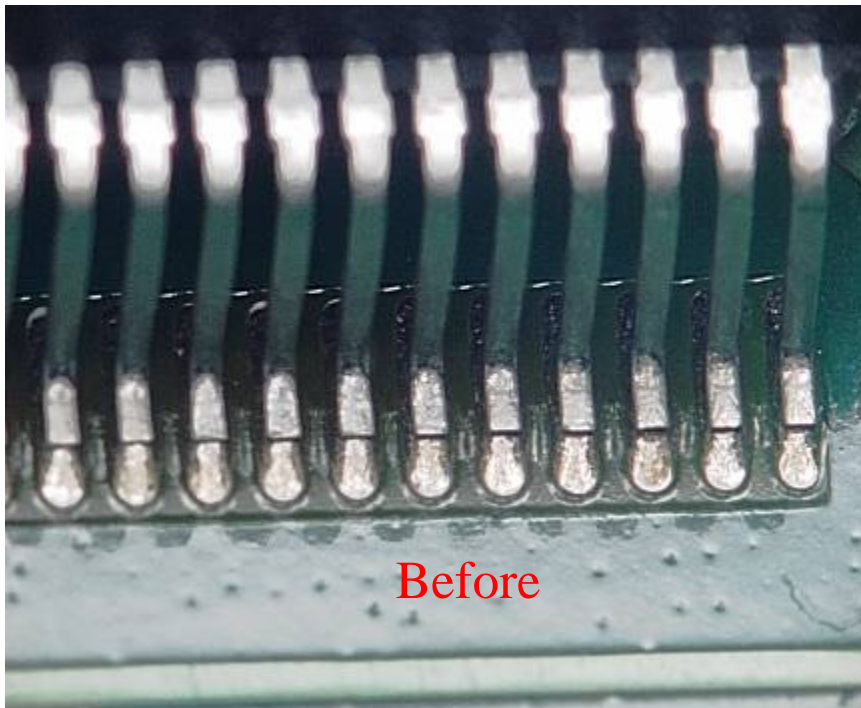
Chemistry 2

- Low Reflow Profile (Peak 230°C)
- One reflow exposure
- 8 minute wash time, 150°F, 20%



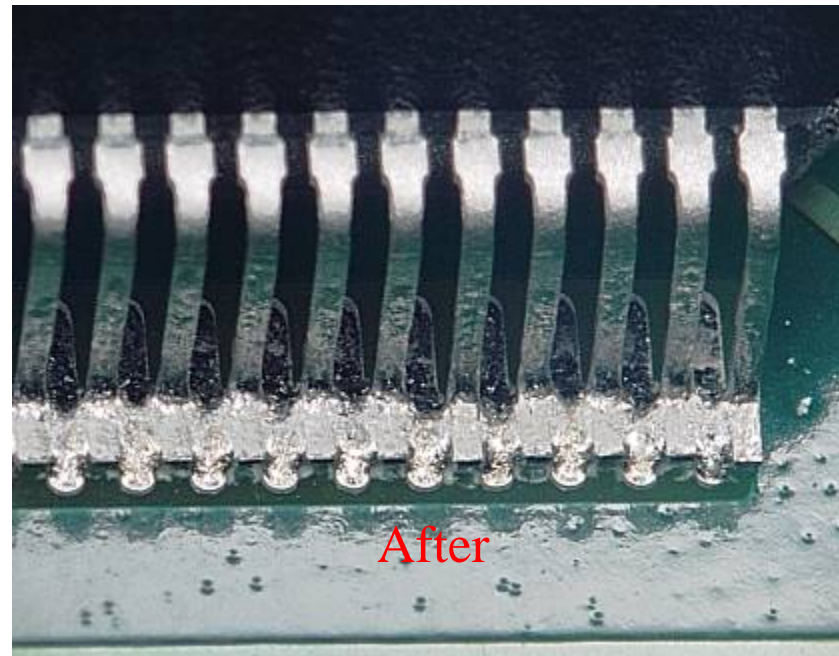
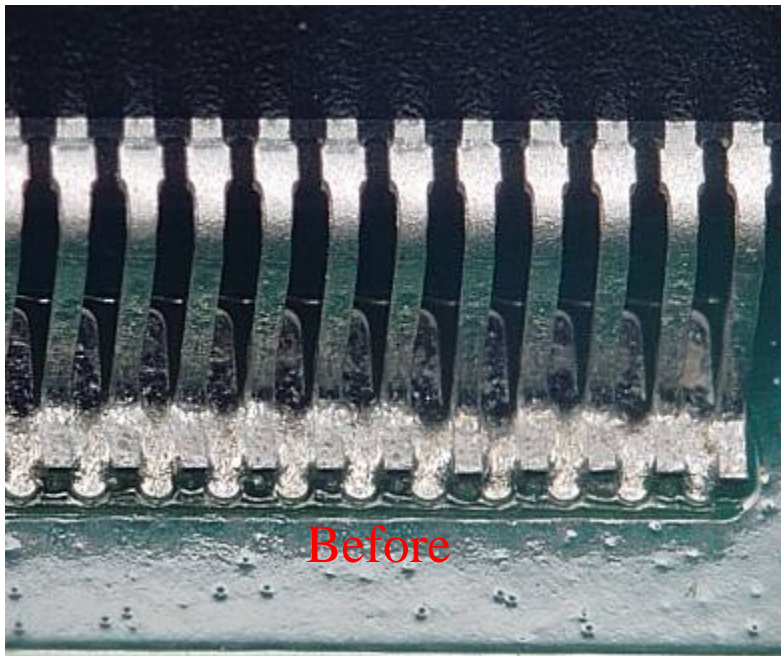
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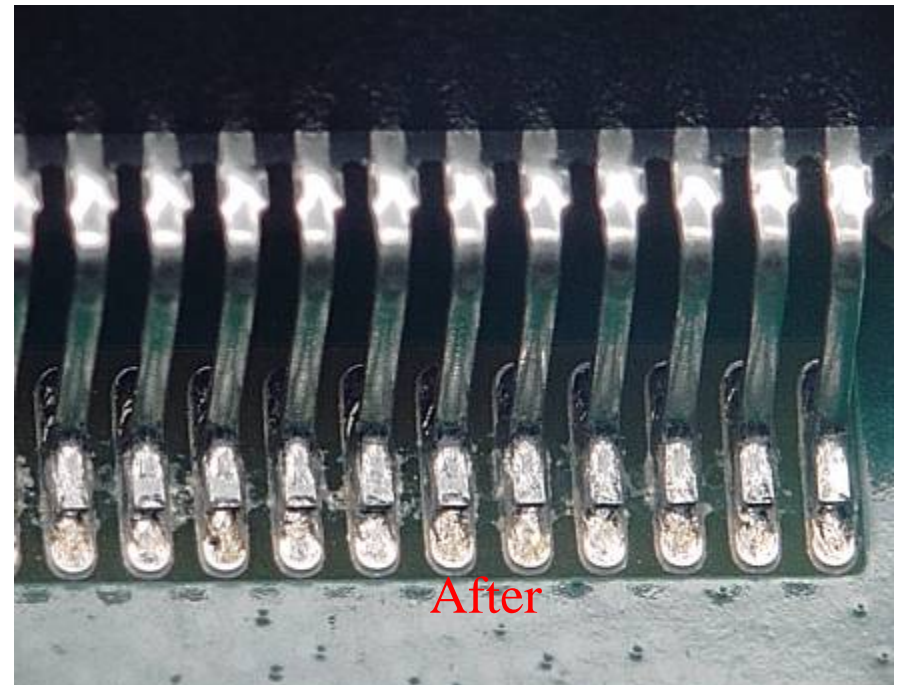
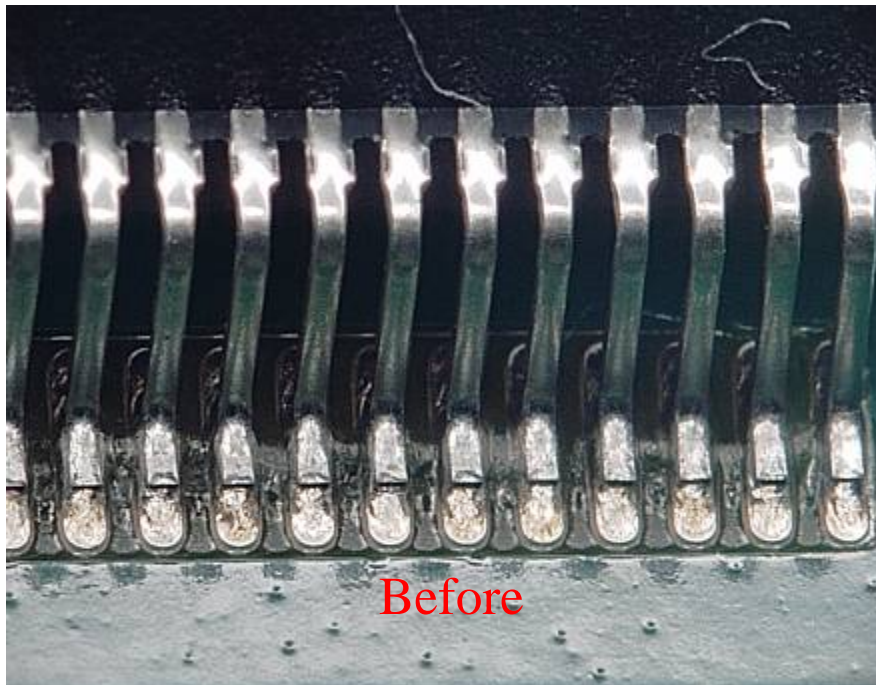
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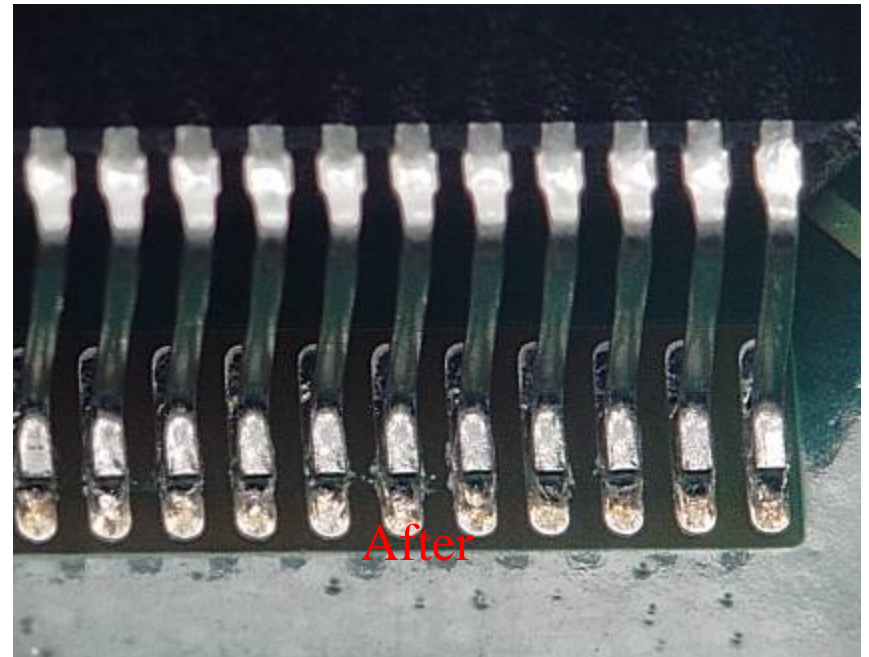
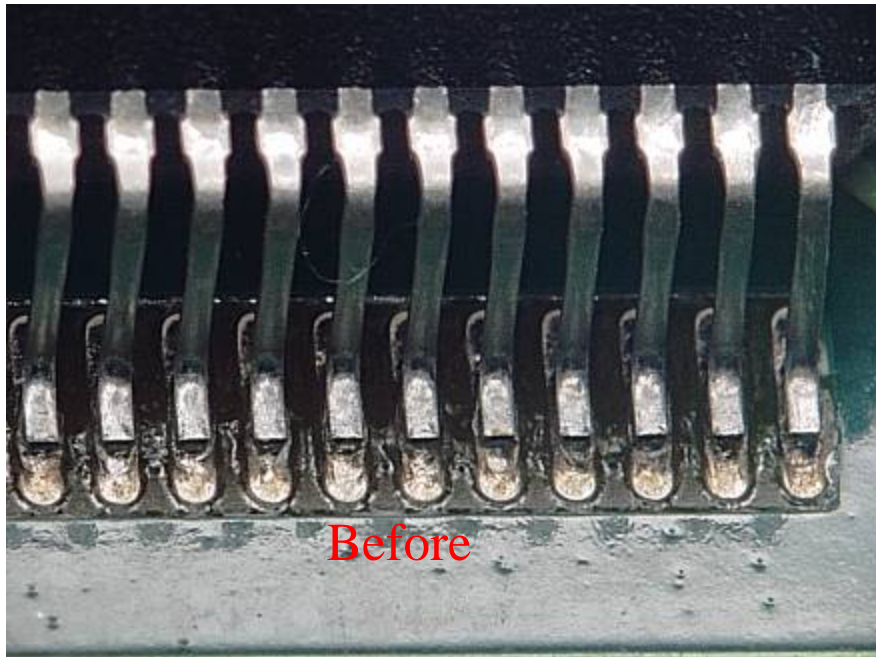
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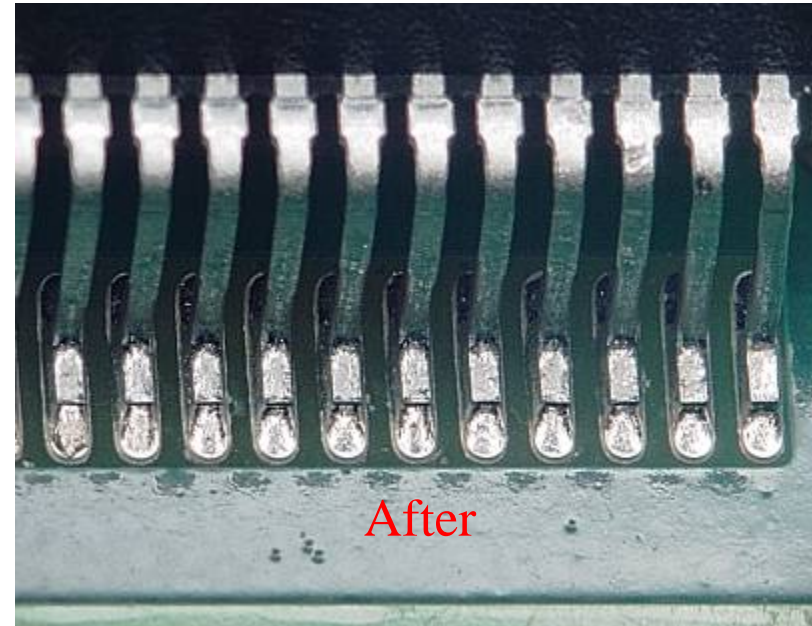
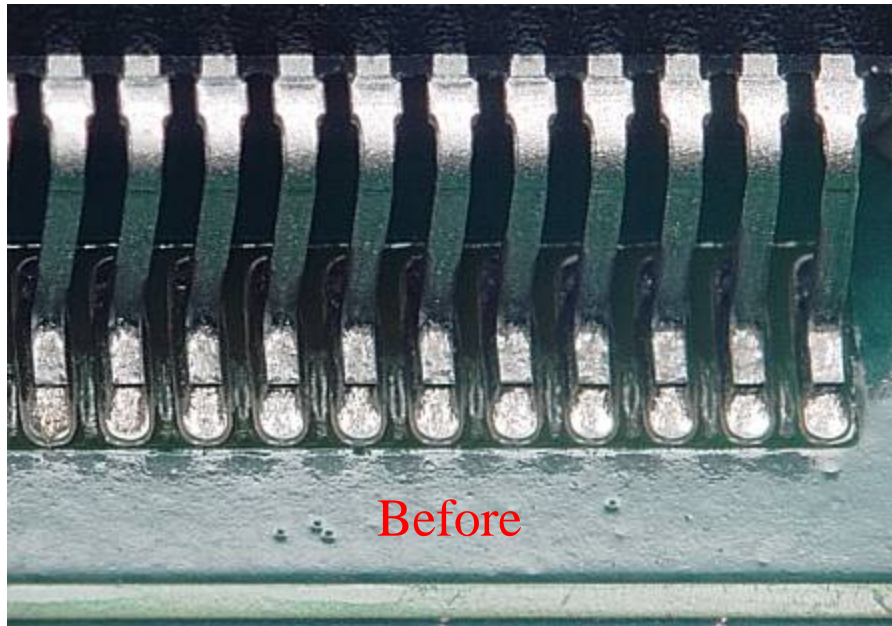
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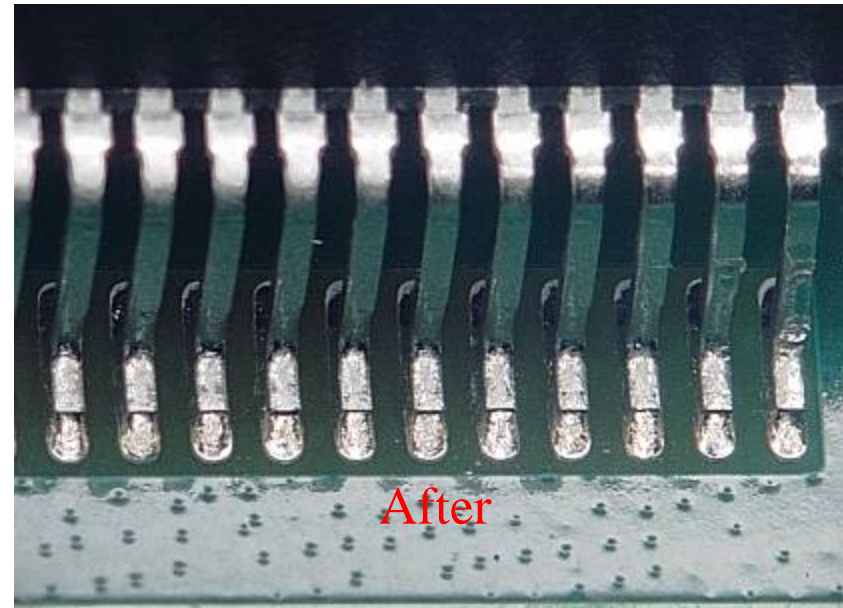
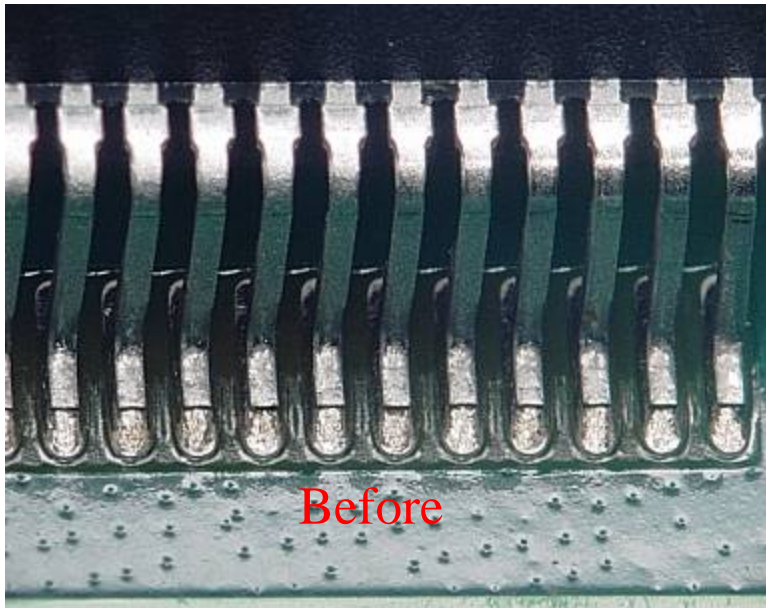
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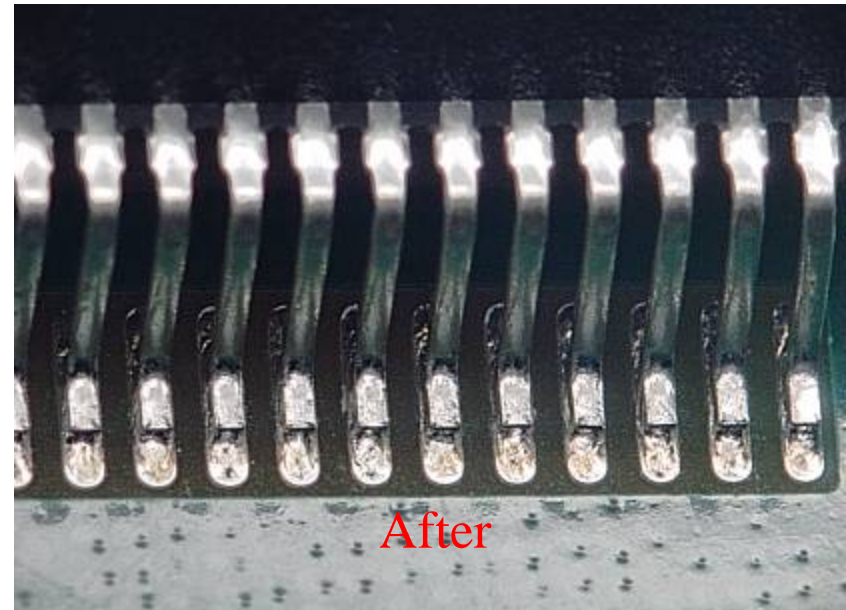
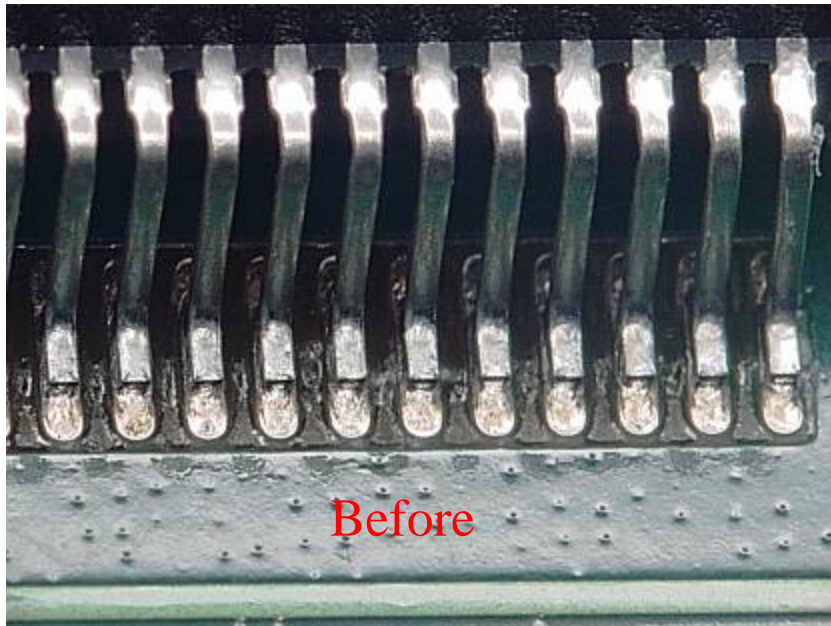
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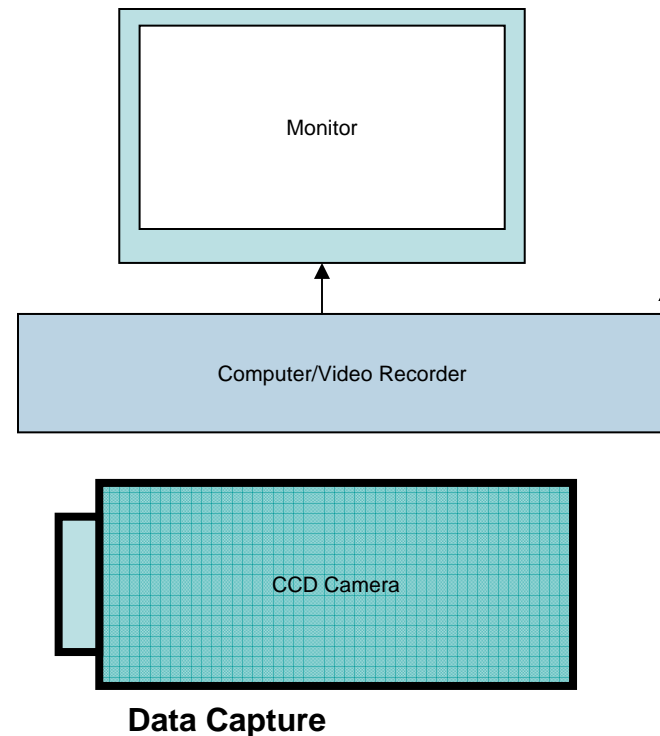
Outcome Table

Run	QFP Visual Exam (1-10)	QFP 90 Visual Exam (1-10)
1	1	1
2	1	1
3	2	1
4	2	1
5	2	1
6	3	1
7	2	3
8	2	2
9	7	5
10	9	8
11	9	8
12	7	7
13	10	9
14	10	10
15	10	10
16	10	10

Dynamic Cleaning Rate

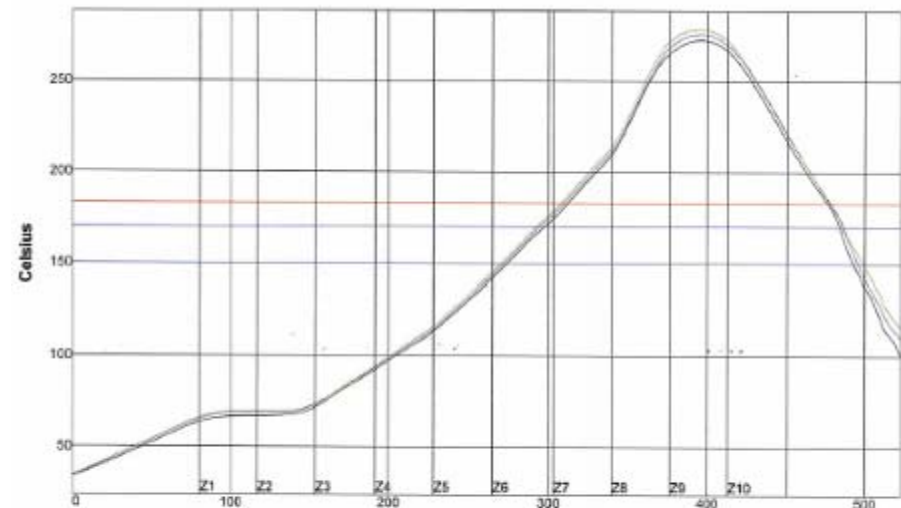
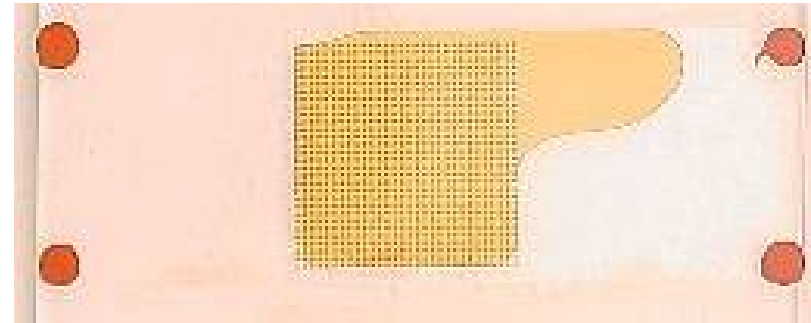
Cleaning Analysis Recording Lab

- Visual evidence of the influence of
 - Cleaning fluid
 - Wash temperature
 - Wash time
 - Nozzle types
 - Spray pressure
 - Movement variations



Test Vehicle

- Glass substrates prepared
 - Slides were bumped with epoxy
 - 75 mm pitch
 - 900 I/O
 - Die size 25mm x 25mm
 - Alpha 615-50
 - Reflowed with Pb-free profile
 - Peak reflow temp 278°C


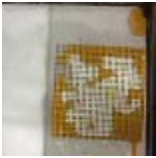






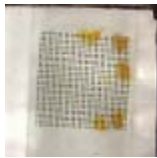
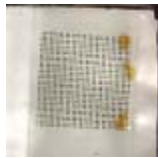


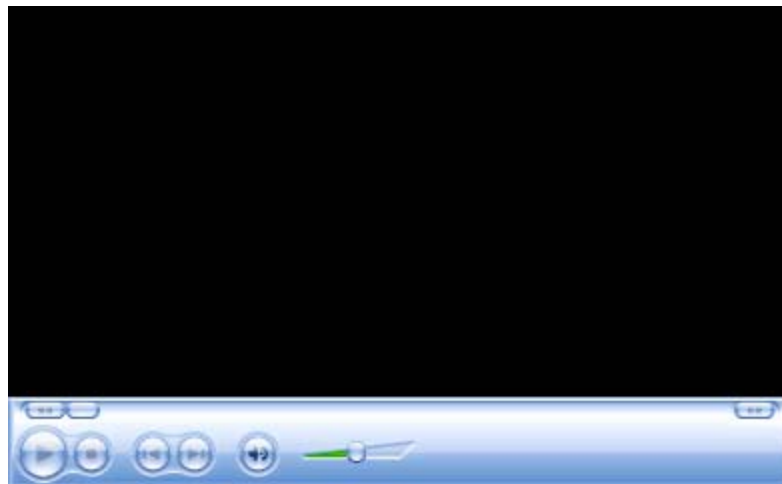
Seconds							
PWI= 606%	Max Rising Slope	Soak Time 150-170C	Reflow Time /183C	Peak Temp			
3	1.8	152%	22.1	-25%	158.5	352%	276.2
4	1.8	161%	21.9	-27%	170.6	369%	278.6
5	1.8	152%	23.1	-23%	154.9	350%	272.8
Delta	0.0	1.1	5.7	5.8			

Factorial Design











Nozzle	Pressure	Wash Temperature	Visual Image Before Cleaning	Time in seconds	Time in seconds	Time in seconds	Time in seconds
1	1	150°F	BC	15	30	45	60
1	2	150°F	BC	15	30	45	60
2	1	150°F	BC	15	30	45	60
2	2	150°F	BC	15	30	45	60
3	1	150°F	BC	15	30	45	60
3	2	150°F	BC	15	30	45	60
4	1	150°F	BC	15	30	45	60
4	2	150°F	BC	15	30	45	60
5	1	150°F	BC	15	30	45	60
5	2	150°F	BC	15	30	45	60
6	1	150°F	BC	15	30	45	60
6	2	150°F	BC	15	30	45	60

Nozzle 1

Nozzle	Before Cleaning	15 seconds	30 seconds	45 seconds	1 minute
Nozzle 1 Pressure 1					
Nozzle 1 Pressure 2					

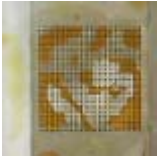

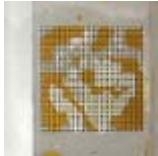









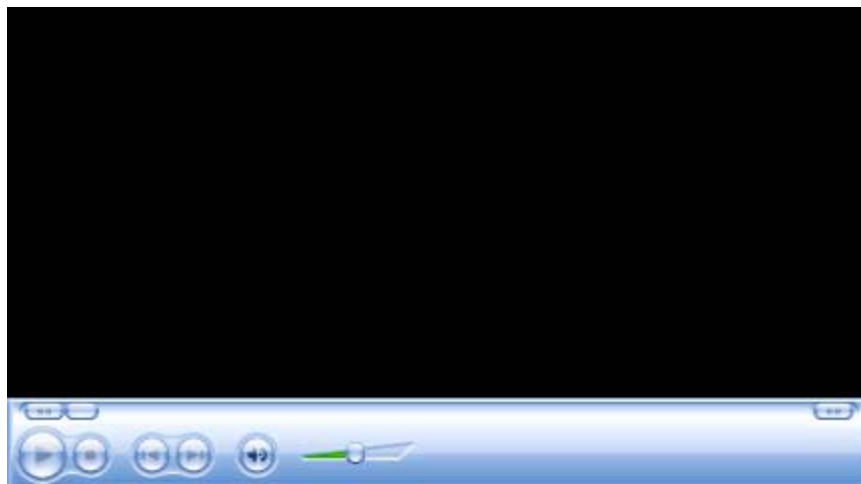
Nozzle 2

Nozzle	Before Cleaning	15 seconds	30 seconds	45 seconds	1 minute
Nozzle 1 Pressure 1					
Nozzle 1 Pressure 2					













Nozzle 3

Nozzle	Before Cleaning	15 seconds	30 seconds	45 seconds	1 minute
Nozzle 1 Pressure 1					
Nozzle 1 Pressure 2					

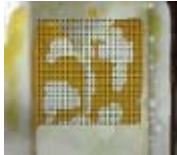
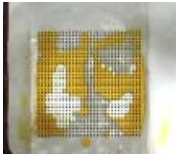
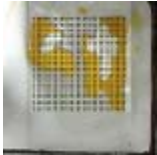
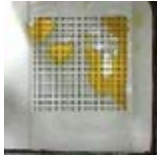
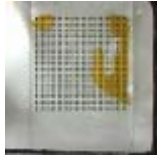







Nozzle 4

Nozzle	Before Cleaning	15 seconds	30 seconds	45 seconds	1 minute
Nozzle 1 Pressure 1					
Nozzle 1 Pressure 2					


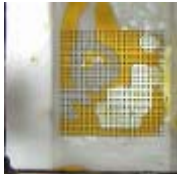
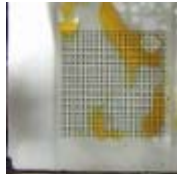

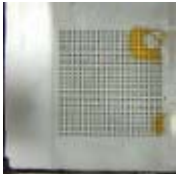



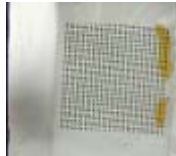
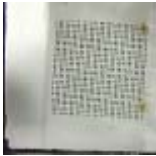


Nozzle 5

Nozzle	Before Cleaning	15 seconds	30 seconds	45 seconds	1 minute
Nozzle 1 Pressure 1					
Nozzle 1 Pressure 2					



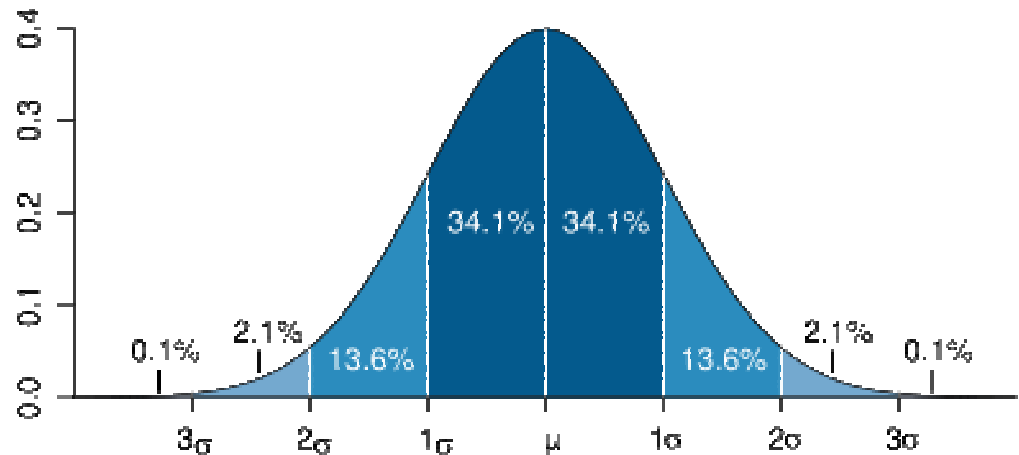
Nozzle 6

Nozzle	Before Cleaning	15 seconds	30 seconds	45 seconds	1 minute
Nozzle 1 Pressure 1					
Nozzle 1 Pressure 2					



Impingement Data Findings

- Three variables influence the cleaning rate
 - Nozzle selection
 - Flow
 - Pressure
- Focal point at the center
 - Fastest cleaning rate
 - Distance from focal point cleaning drops off



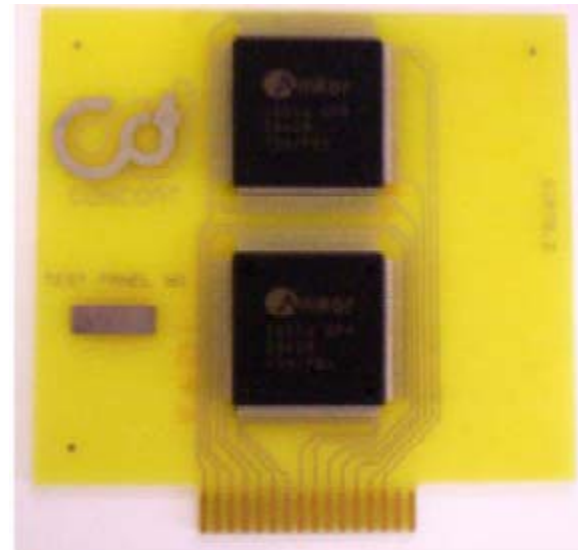
Optimization

- **Step 1: Upstream process conditions**
 - Substrate, contaminate, reflow
- **Step 2: Static cleaning rate**
 - Rate of solubility in the absence of strong impingement forces
- **Step 3: Dynamic cleaning rate**
 - Fluid flow, pressure, and directional forces
- **Process cleaning rate = static rate + dynamic rate**

Validation

Cleanliness & Electrical Performance

- Concoat Test Board
- Ion Chromatography: IPC-TM-650
 - 4 test boards
- Surface Insulation Resistance: IPC-TM-650



IC Data Findings

Table #1: PAL Recommended Cleanliness Guidelines

PAL's Recommended Cleanliness Guidelines						
Condition	Cl	Br	NO3	PO4	SO4	Organic Acids
Bare Board (Cold plating)	< 1.0	< 12.0	< 3-5.0	PI	< 3-5.0	PI
Bare Board (HASL)	< 2.0	< 12.0	< 3-5.0	PI	< 3-5.0	PI
Assembly (No clean)	< 2.5	< 12.0	< 3-5.0	PI	< 3-5.0	20-50.0
Assembly (Water-soluble / RMA)	< 4-5.0	< 12.0	< 3-5.0	PI	< 3-5.0	20-50.0

Table #1: All values reported in $\mu\text{g}/\text{in}^2$. Cold plating refers to immersion Ag, immersion Sn, and ENIG. PI indicates that the component is treated as a process indicator as there are no industry guidelines currently available.

Ion Chromatography Data:

Table #2: Numerical Anion Chromatography Data

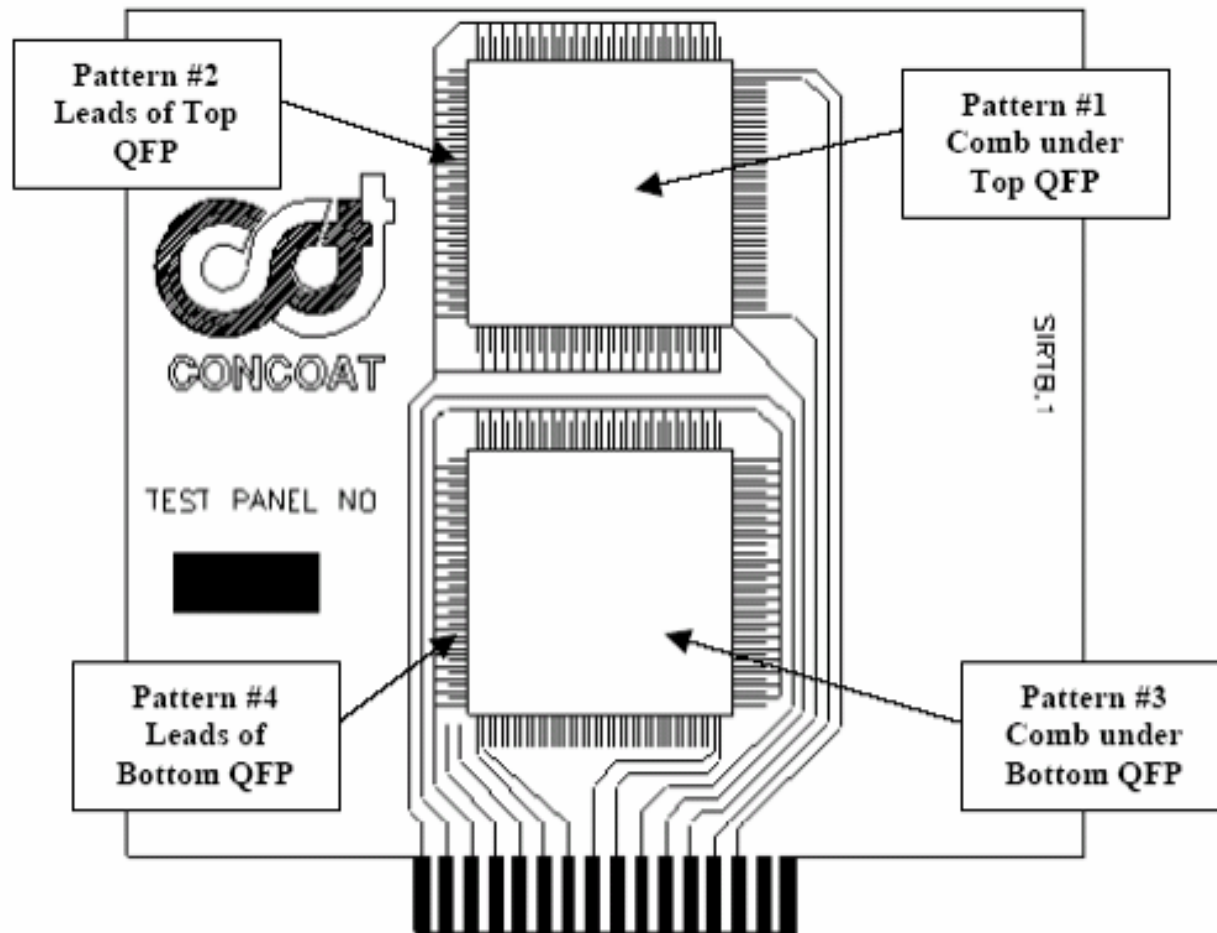
Sample Number	Sample Description	Extract Vol (mL)	Area (in^2)	Dilution Factor	Chloride Cl	Bromide Br	Nitrate NO3	Phosphate PO4	Sulfate SO4	Organic Acid
Blank	Kapak 502	10.00	72.00	0.14	ND	ND	ND	ND	0.06	ND
3106-009-01	Control	20.00	31.31	0.64	2.31	1.32	0.15	ND	ND	1.85
3106-009-02	Brd #1	20.00	31.31	0.64	1.37	1.04	0.14	ND	ND	1.03
3106-009-03	Brd #2	20.00	31.31	0.64	1.19	0.92	0.14	ND	ND	1.28
3106-009-04	Brd #3	20.00	31.31	0.64	1.26	1.00	0.13	ND	ND	1.06

Table #2: All ion values reported in the table are in $\mu\text{g}/\text{in}^2$. ND = None Detected. All bag blank contaminants have been subtracted from the sample amounts.

IC Data Conclusion

- All boards showed very low levels of ionic contamination
- The cleaned samples showed consistently lower amounts
 - Chloride
 - Bromide
- Nitrate levels were unremarkable and not of any concern
- Organic acid showed slight improvements compared to control board

SIR Patterns



SIR Data Findings

Sample ID	Resistance Readings (Ohms)					
	Pattern	Initials	24 Hours	96 Hours	168 Hours	Finals
		5/22/2007	5/23/2007	5/26/2007	5/29/2007	5/29/2007
Control	1	4.13E+10	1.78E+07	1.39E+08	1.49E+08	1.18E+09
	2	1.73E+12	2.44E+08	4.76E+08	4.00E+08	1.03E+12
	3	1.56E+09	6.71E+07	5.62E+07	3.73E+07	8.62E+10
	4	1.24E+12	1.54E+08	2.56E+08	2.78E+08	4.44E+12
Cleaned Brd #1	1	9.99E+11	5.00E+08	6.28E+08	6.16E+08	1.60E+12
	2	4.16E+12	3.89E+09	1.81E+09	1.27E+09	2.22E+12
	3	3.53E+10	5.00E+08	6.16E+08	6.69E+08	1.09E+11
	4	3.02E+12	3.44E+09	1.52E+09	1.30E+09	1.76E+12
Cleaned Brd #2	1	1.74E+12	3.33E+08	5.26E+08	5.96E+08	4.35E+11
	2	1.17E+13	3.02E+09	1.67E+09	1.35E+09	1.62E+12
	3	4.67E+10	2.56E+08	4.76E+08	5.26E+08	1.61E+11
	4	4.94E+12	2.90E+09	1.41E+09	1.14E+09	1.18E+12
Cleaned Brd #3	1	6.47E+12	4.17E+08	6.15E+08	6.44E+08	1.32E+12
	2	1.08E+13	2.91E+09	1.64E+09	1.26E+09	3.66E+12
	3	3.65E+10	3.57E+08	6.08E+08	6.45E+08	1.64E+11
	4	9.77E+12	2.60E+09	1.43E+09	1.22E+09	2.50E+12
Cleaned Brd #4	1	2.45E+12	3.57E+08	6.28E+08	7.11E+08	2.05E+12
	2	4.98E+12	3.76E+09	2.07E+09	1.52E+09	2.10E+12
	3	3.48E+10	3.13E+08	5.26E+08	6.64E+08	1.54E+11
	4	2.26E+12	2.60E+09	1.76E+09	1.43E+09	1.80E+12
Cleaned Brd #5	1	1.64E+12	2.86E+08	4.35E+08	4.55E+08	4.76E+11
	2	2.61E+12	2.33E+09	1.35E+09	1.09E+09	1.99E+12
	3	3.70E+10	3.33E+08	5.26E+08	5.56E+08	1.75E+11
	4	3.08E+12	2.27E+09	1.27E+09	1.08E+09	2.02E+12

SIR Data Conclusion

- Initial measures verify test boards are returning good readings
- 24 hour results are expected to drop as boards acclimate to environmental conditions
- 96 hour cleaned boards showed slight improvement and were above the pass limit
- 168 hour cleaned boards maintained and were passing
- All cleaned boards returned high readings and passed.

Conclusion

- **Cleaning process optimization requires an understanding of**
 - Upstream processing conditions
 - Static cleaning rate
 - Dynamic cleaning rate
- **Improved cleaning fluids**
 - Higher static cleaning rate
 - Lower surface tension
 - Clean Pb-free flux soils
- **Improved cleaning equipment**
 - Optimize flow, pressure, and directional forces
- **Result**
 - Broader processing window to addressing challenging cleaning needs

References

- Bixenman, M., Gervascio, T., Lasky, R. (2007). Using six sigma to optimize cleaning in Class III manufacturing environments. SMTAI Technical Forum, Gaylord Palms Resort and Convention Center, Orlando Florida
- IPC, (2006-2007). IPC international technology roadmap for electronic interconnections. Retrieved from www.ipc.org
- Stach, S., & Bixenman, M. (2005, Sep). Optimizing cleaning energy in electronic assembly spray in air systems: Phase II. SMTAI Technical Forum, Rosemont, IL, Donald Stephens Convention Center.

Author

**Mike Bixenman, DBA
Chief Technology Officer
Kyzen Corporation
430 Harding Industrial Drive
Nashville, TN 37211
mikeb@kyzen.com**